



Faculty of Engineering \ School of Photovoltaic and Renewable Energy Engineering  
Advanced Hydrogenation Group

# Understanding the boron-oxygen defect: properties, kinetics and deactivation mechanisms

SPREE Seminar

University of New South Wales  
Sydney, Australia

**9 November 2017**

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Supervisors: Malcolm Abbott, Stuart Wenham,  
Matthew Edwards



# Motivation

- *p*-type silicon dominant for foreseeable future

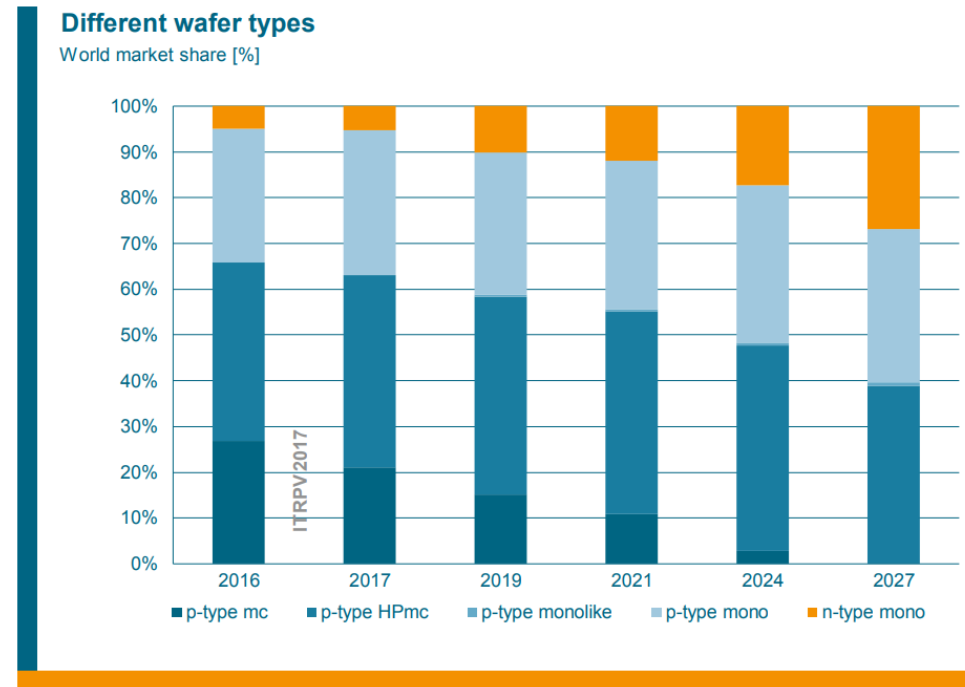


Fig. 36: World market shares for different wafer types.

# Motivation

- $p$ -type silicon dominant for foreseeable future
- PERC cells seeing an increasing market share

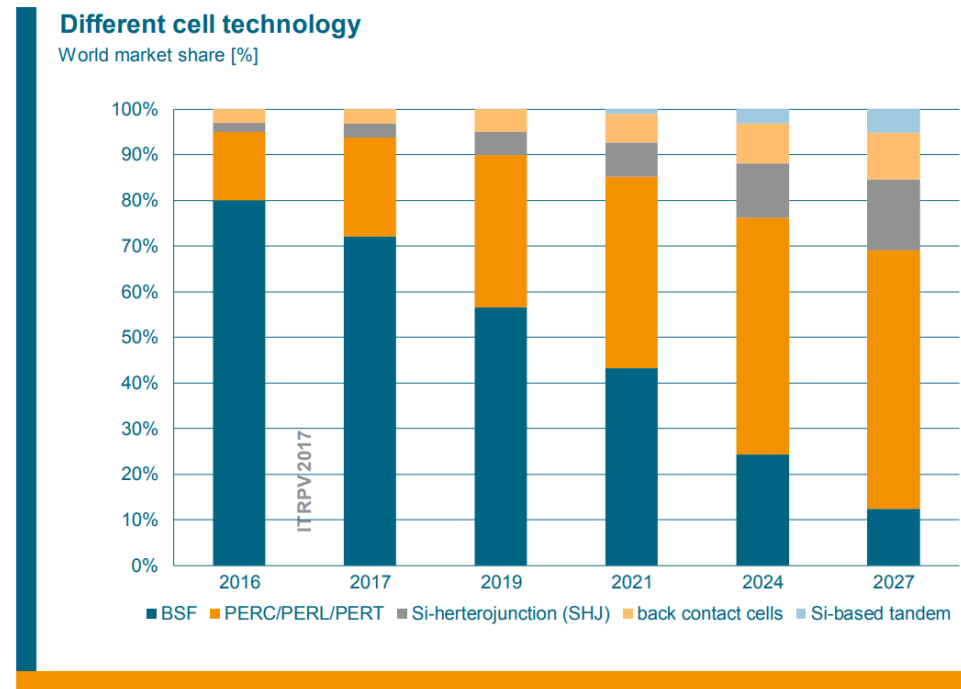


Fig. 41: Worldwide market shares for different cell technologies.

# Motivation

- *p*-type silicon dominant for foreseeable future
- PERC cells seeing an increasing market share
- Surface passivation quality is improving

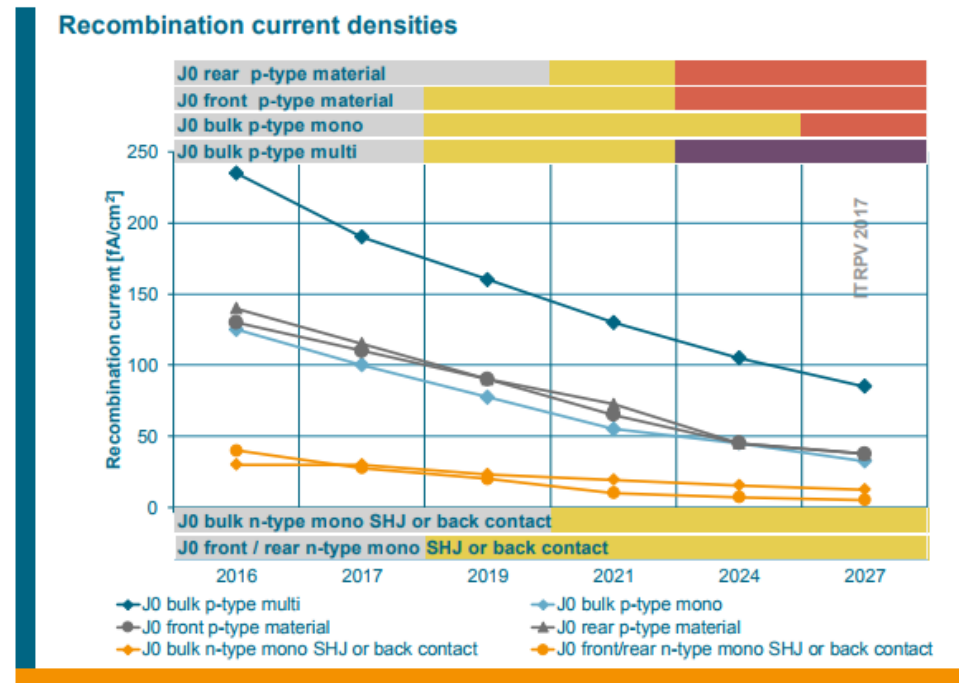


Fig. 25: Predicted trend for recombination currents J0bulk, J0front, J0rear for p-type and n-type cell concepts.

# Motivation

- *p*-type silicon dominant for foreseeable future
- PERC cells seeing an increasing market share
- Surface passivation quality is improving

→ Strong imperative to:

- Improve bulk quality
- Minimise cell degradation

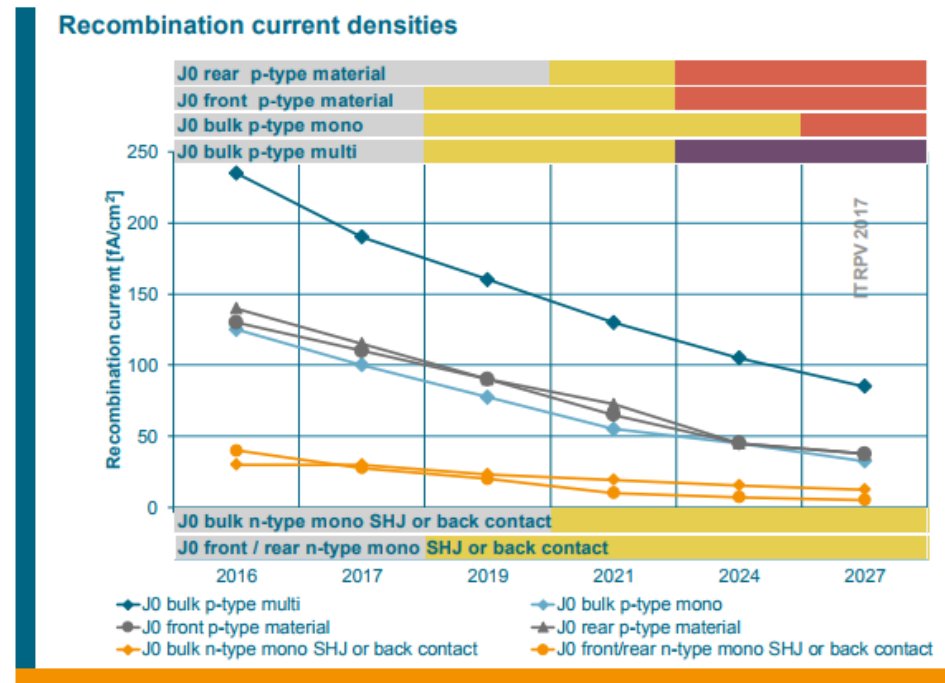


Fig. 25: Predicted trend for recombination currents  $J_0$ bulk,  $J_0$ front,  $J_0$ rear for p-type and n-type cell concepts.

# Motivation

- Boron-oxygen defects are the most important source of LID in commercial Cz solar cells

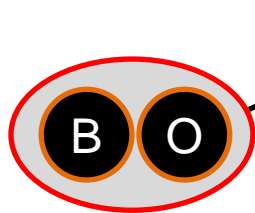
- Cell efficiency loss:

- PERC: 1-12%<sub>rel</sub>
- Al-BSF: 1-6%<sub>rel</sub>

**Mitigation of BO defects is of vital importance**

- For a cell manufacturer producing 1,000 MW<sub>p</sub>/year:
  - 60-120 MW<sub>p</sub>/year in lost production
  - USD \$12-24 million/year in lost savings

# The boron-oxygen defect



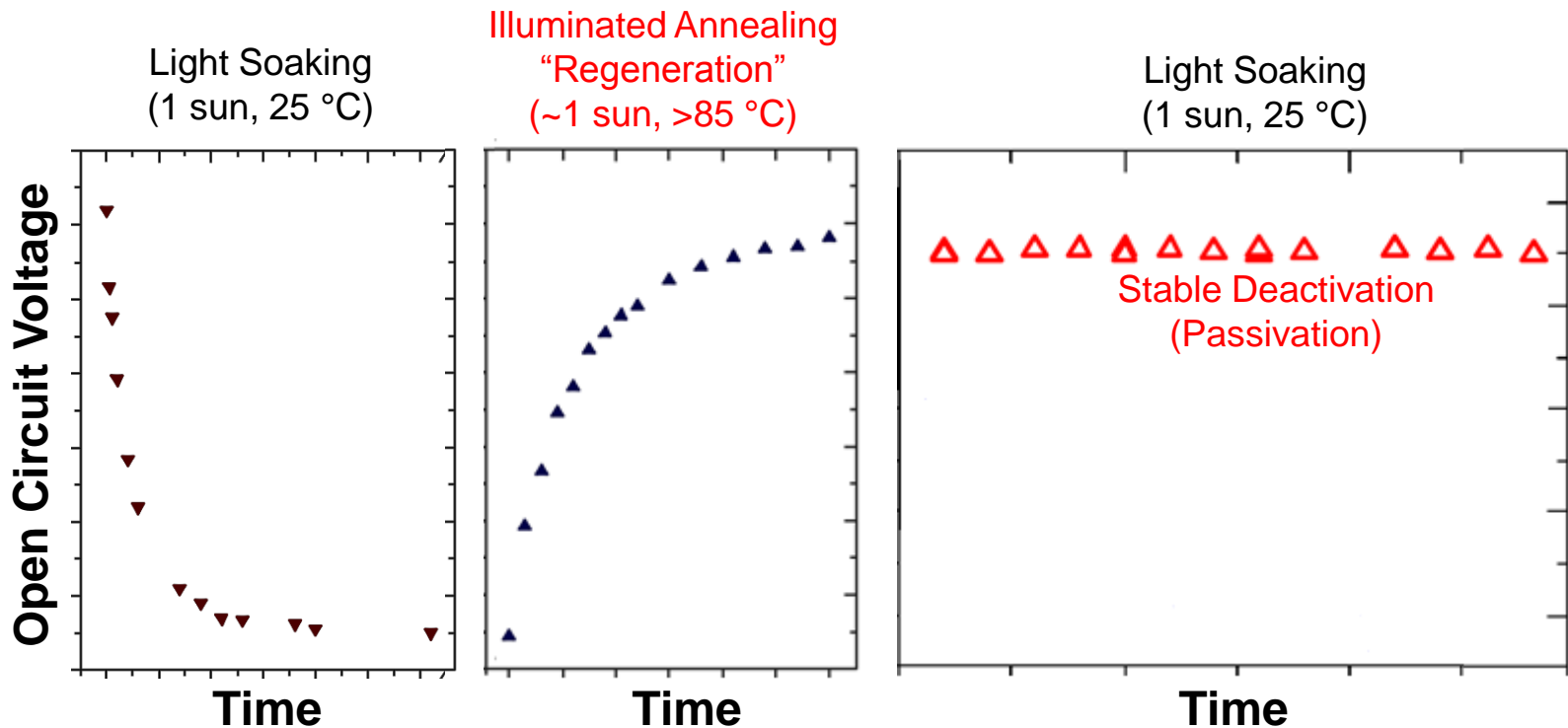
causes

Light Induced Degradation

but can be...

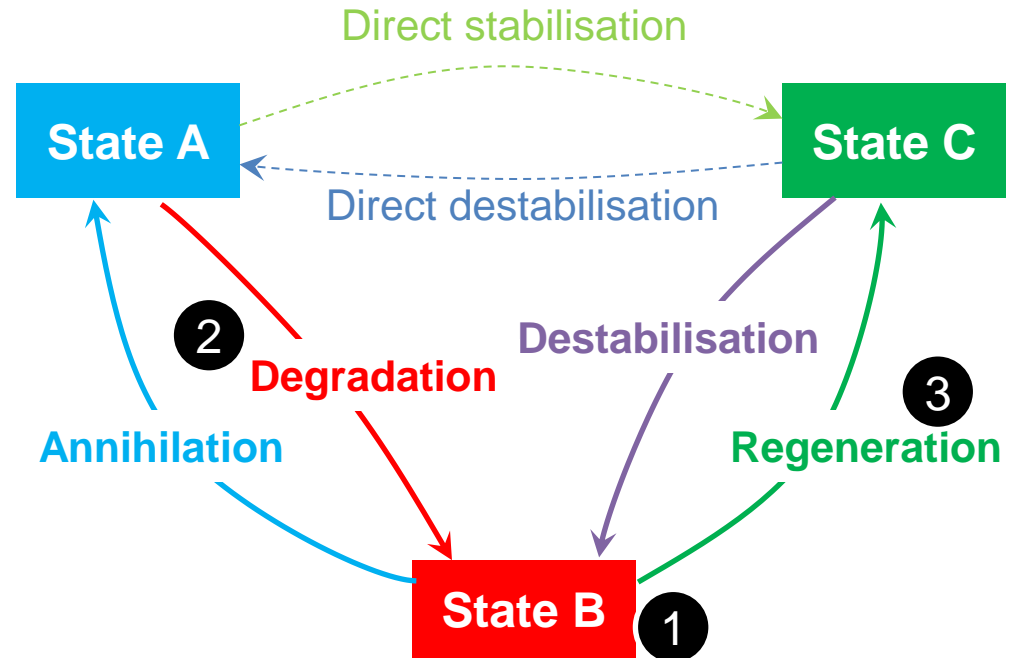
Temporarily Deactivated

Permanently Deactivated



# The boron-oxygen defect

- Behaviour described by 3-state model
- Focus of this work:
  1. Recombination properties
  2. Reaction kinetics
  3. Deactivation mechanisms







# Recombination properties of the boron-oxygen defect

Never Stand Still

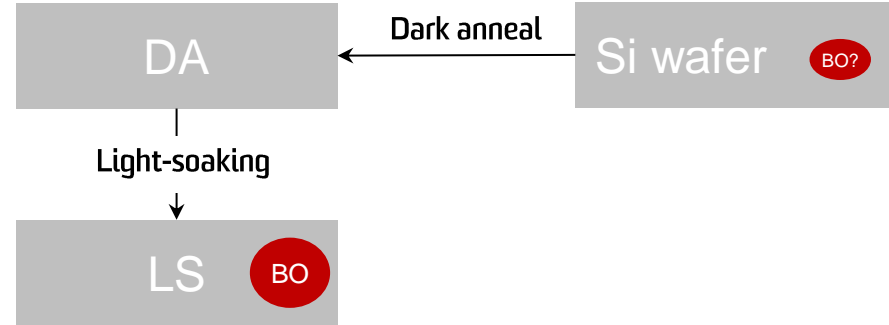
Engineering

# Recombination properties of BO

$$\frac{1}{\tau_{eff,DA}} = \frac{1}{\tau_{surf}} + \frac{1}{\tau_{bulk,non-BO}}$$

$$\frac{1}{\tau_{eff,LS}} = \frac{1}{\tau_{surf}} + \frac{1}{\tau_{bulk,non-BO}} + \frac{1}{\tau_{SRH,BO}}$$

$$\frac{1}{\tau_{SRH}} = \frac{(np - n_i^2)}{\Delta n \cdot [\tau_{p0}(n + n_1) + \tau_{n0}(p + p_1)]}$$



$$p_1 = n_{i,eff} \times e^{\left(\frac{E_i - E_{trap}}{k_B T}\right)}$$

$$\tau_{n0} = \frac{1}{N_{trap} \sigma_n v_{th,e}}$$

$$\tau_{p0} = \frac{1}{N_{trap} \sigma_p v_{th,h}}$$

$$k = \frac{\sigma_n}{\sigma_p}$$

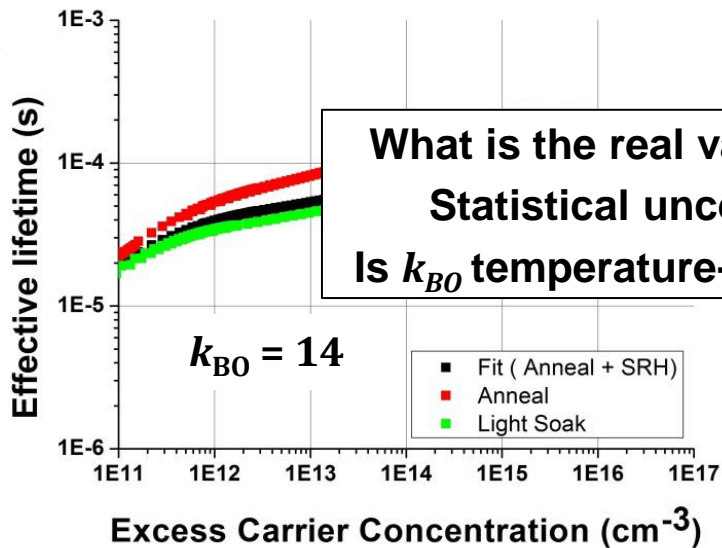
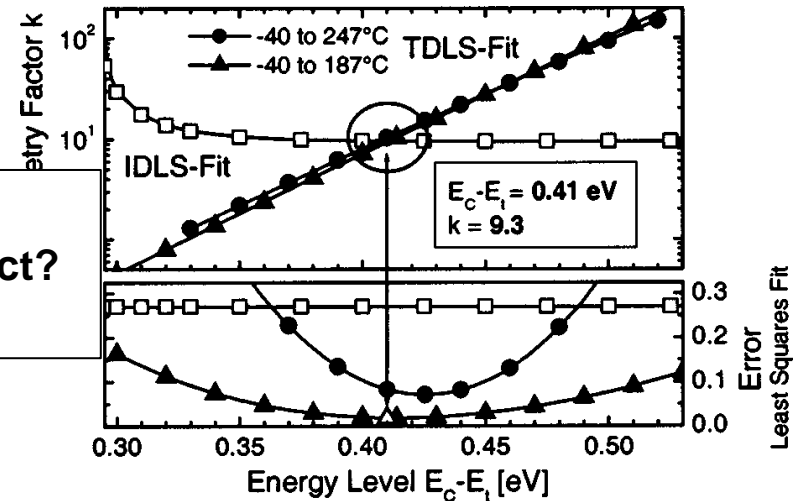
# Recombination properties of BO

$N_{\text{trap}}$

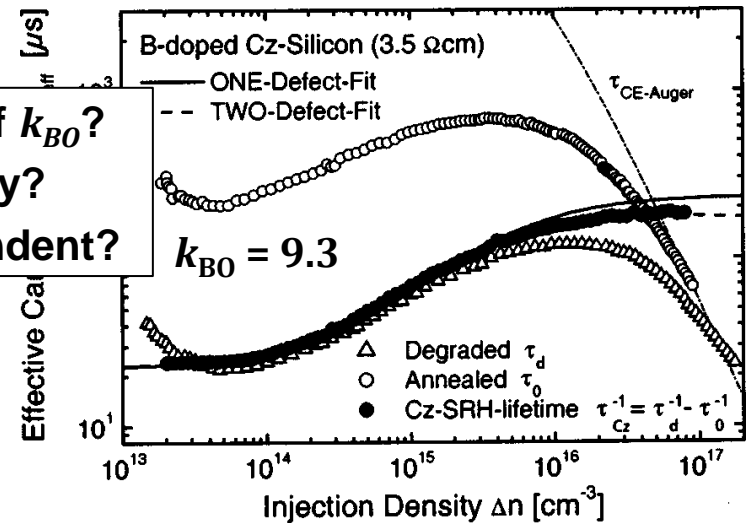
$E_{\text{trap}}$

$k$

Is the value of  $E_{\text{trap},\text{BO}}$  correct?



What is the real value of  $k_{\text{BO}}$ ?  
Statistical uncertainty?  
Is  $k_{\text{BO}}$  temperature-dependent?



# Recombination properties of BO

$$N_{\text{trap}}$$

$$N_{\text{trap}} = \frac{1}{\tau_{n0} \sigma_n v_{th,e}}$$

Value unknown!  
(for BO)

$$E_{\text{trap}}$$

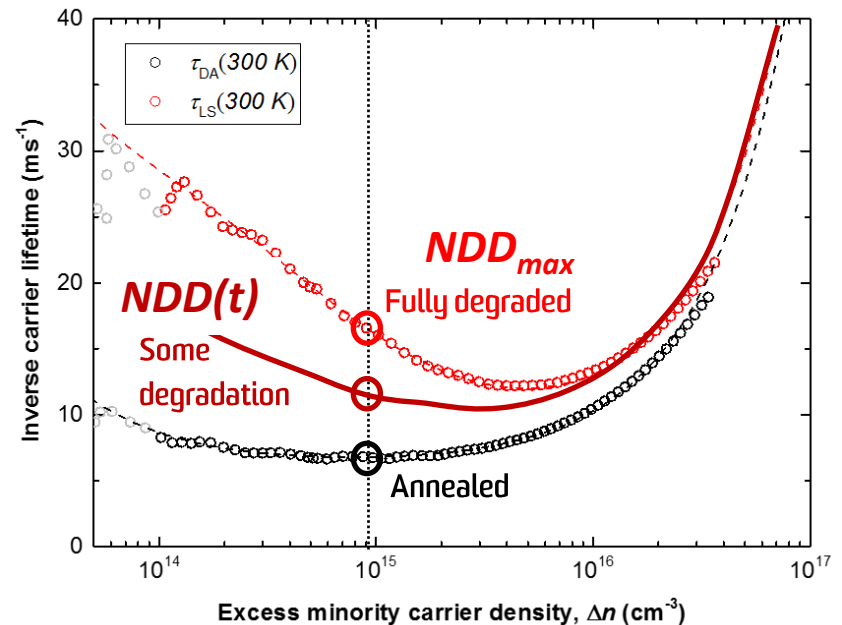
At low injection ( $\Delta n = 0.1 \times N_A$ ):

$$k$$

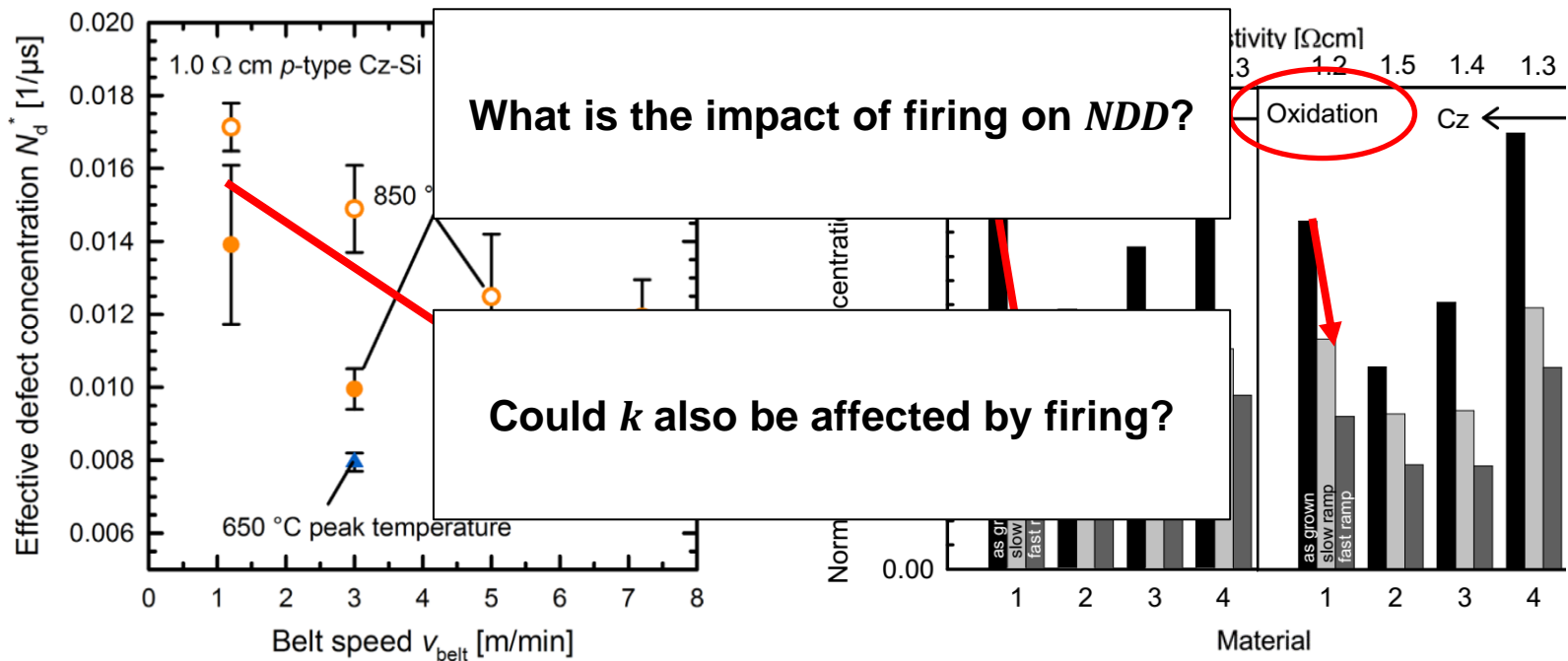
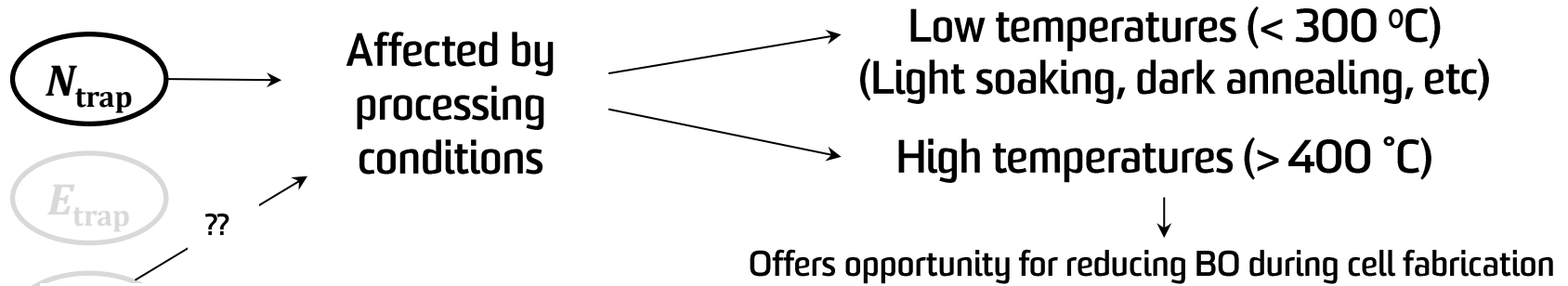
$$N_{\text{trap}} \propto \frac{1}{\tau_{\text{SRH},\text{BO}}}$$

$$\propto \left( \frac{1}{\tau_{\text{LS}}} - \frac{1}{\tau_{\text{DA}}} \right) = \text{NDD}$$

(Normalised Defect Density)



# Recombination properties of BO



# Recombination properties of BO

- SRH properties of the BO defect (  $k$ ,  $E_{trap}$  )
- Impact of firing on  $k$
- Impact of firing on defect density

# Recombination properties of BO

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# SRH Recombination Properties

Methods for determining recombination properties:

- **IDLS**: Injection-Dependent Lifetime Spectroscopy
  - A common characterization method
  - Good sensitivity to  $k$  (if  $E_{\text{trap}}$  is known)
  - Low sensitivity to  $E_{\text{trap}}$  (for mid-gap defects)
- **TDLS**: Temperature-Dependent Lifetime Spectroscopy
  - Good sensitivity to  $E_{\text{trap}}$ ,  $k$
  - Analysis at single injection level ( $\Delta n$ )
- **TIDLS**: Temperature- and Injection-Dependent Lifetime Spectroscopy
  - Best sensitivity to  $E_{\text{trap}}$ ,  $k$
  - Analysis over full range of  $\Delta n$



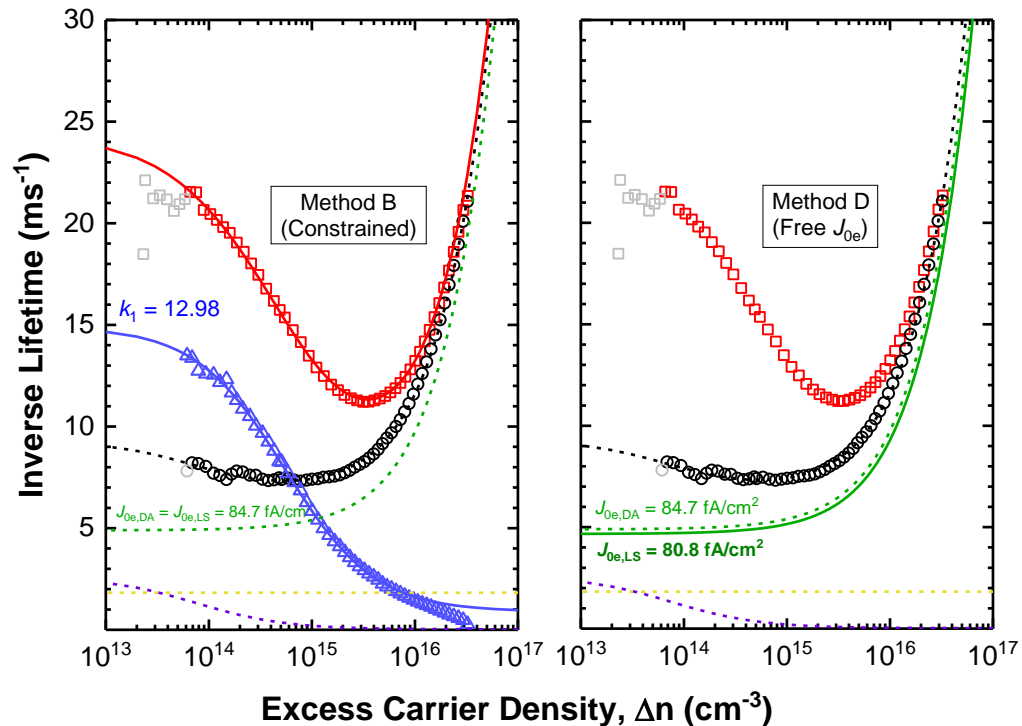
# SRH Recombination Properties

## IDLS analysis

$$\frac{1}{\tau_{DA}} = \frac{1}{\tau_{surf}} + \frac{1}{\tau_{bulk, fixed}} + \frac{1}{\tau_{SRH, non-BO}}$$

$$\frac{1}{\tau_{LS}} = \frac{1}{\tau_{surf}} + \frac{1}{\tau_{bulk, fixed}} + \frac{1}{\tau_{SRH, non-BO}} + \frac{1}{\tau_{SRH, BO}}$$

Allow this to vary

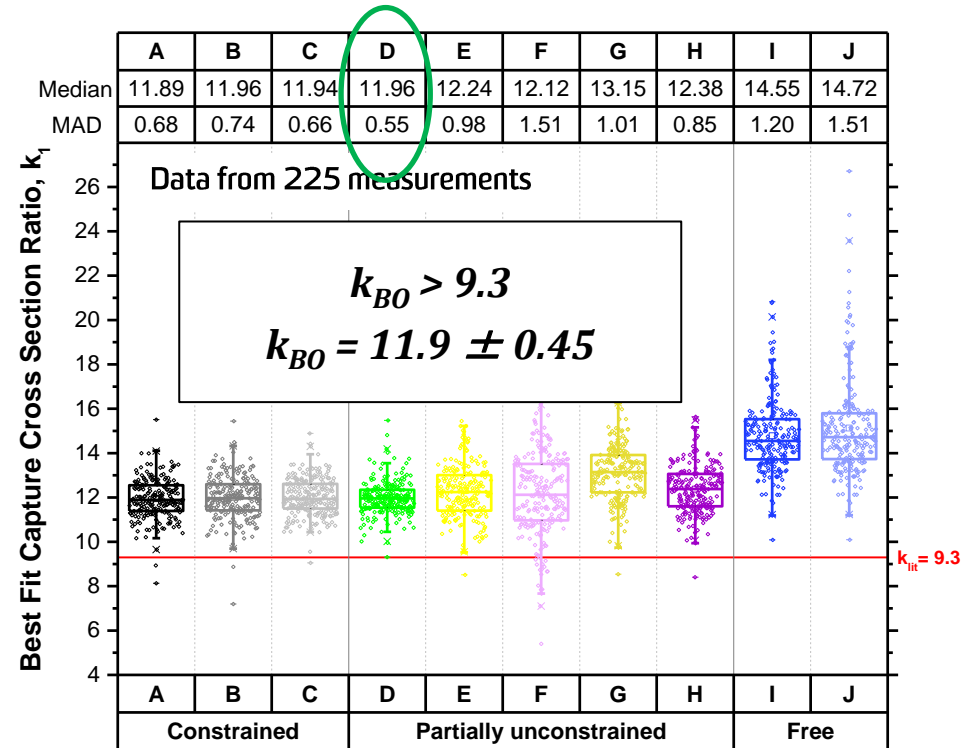
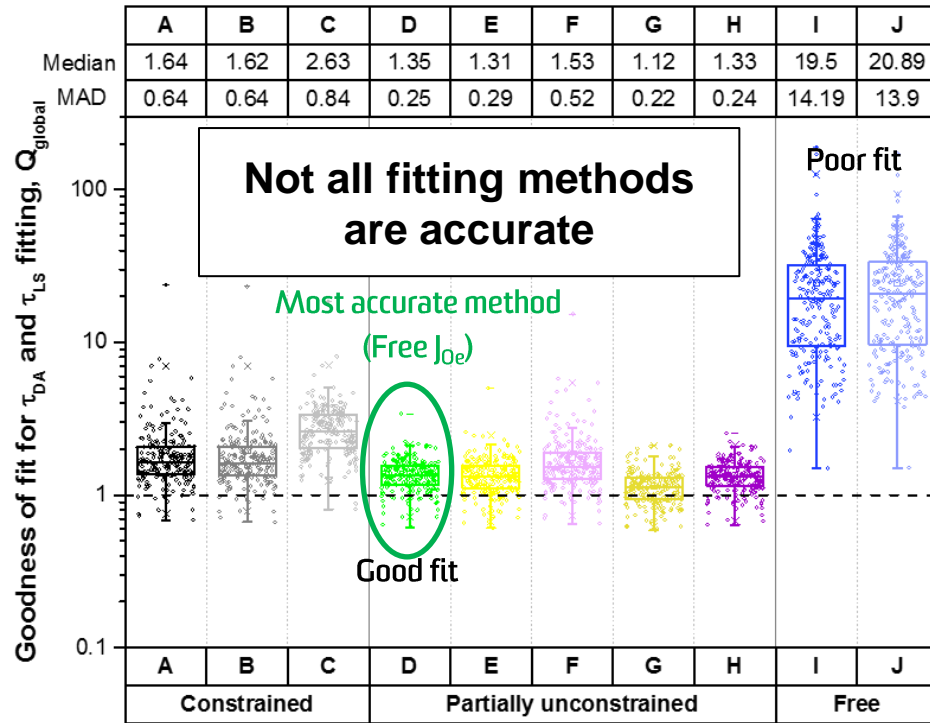


# SRH Recombination Properties

## IDLS analysis

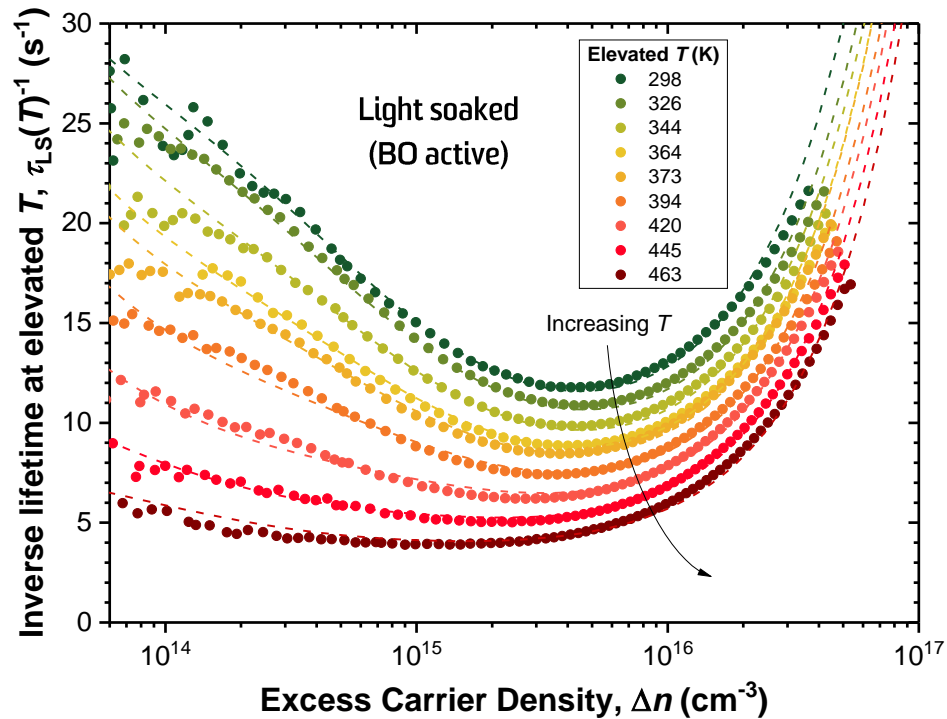
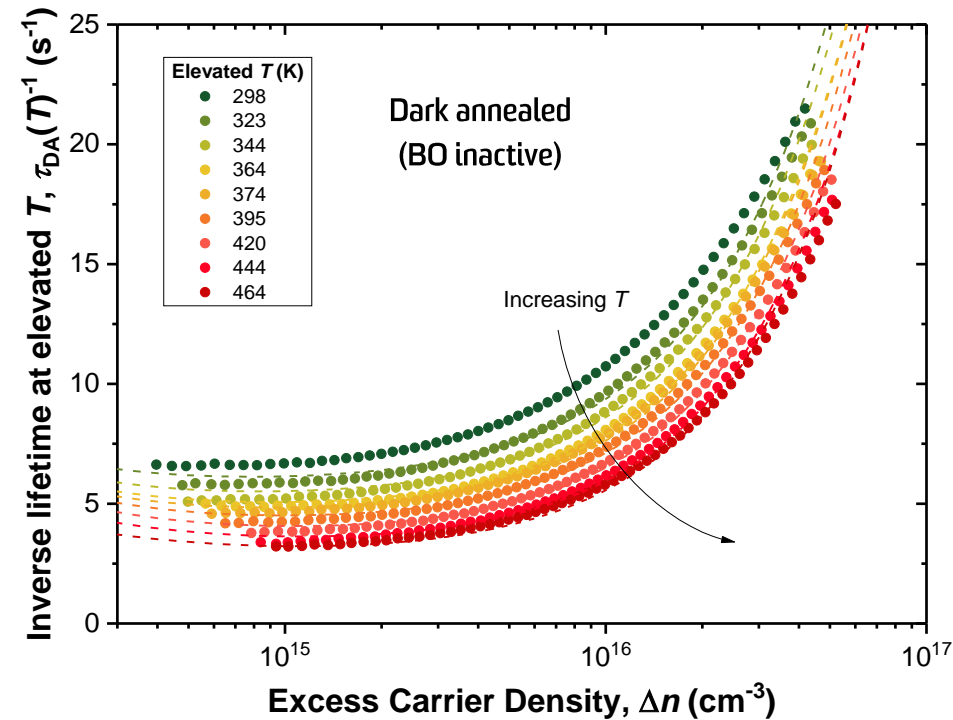
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$$\frac{1}{\tau_{LS}} = \frac{1}{\tau_{surf}} + \frac{1}{\tau_{bulk, fixed}} + \frac{1}{\tau_{SRH, non-BO}} + \frac{1}{\tau_{SRH, BO}}$$



# SRH Recombination Properties

## TIDLS analysis



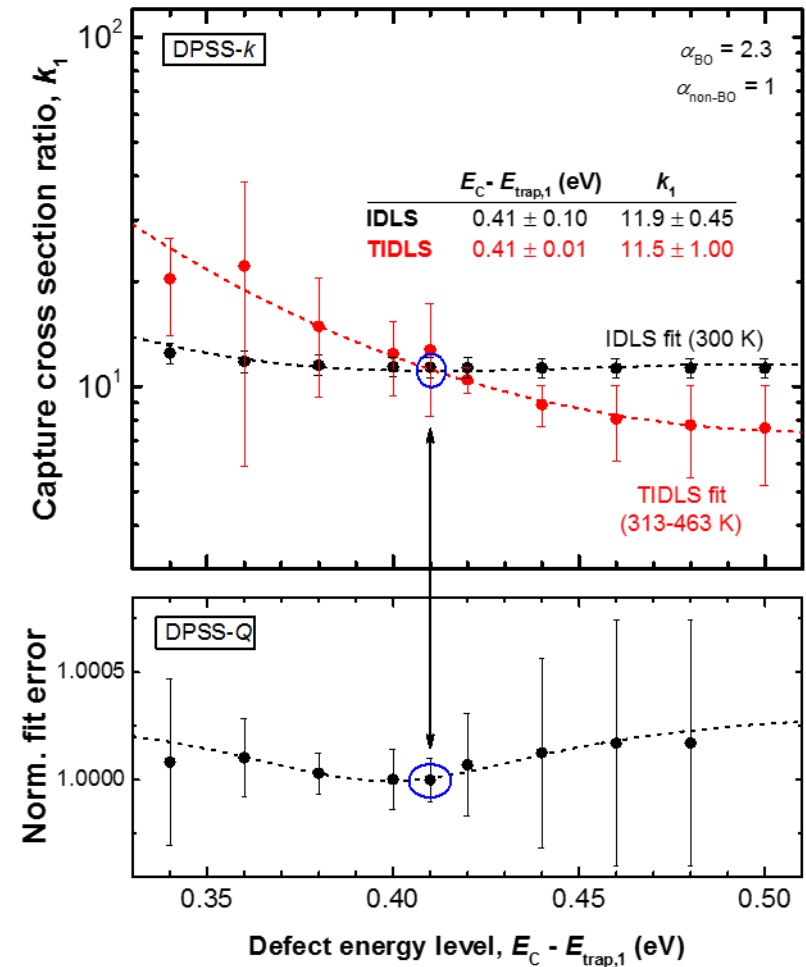
# SRH Recombination Properties

## TIDLS analysis

- Determine  $E_{trap}$ ,  $k$

$$E_C - E_{trap} = 0.41 \pm 0.10$$

$$k_{BO} = 11.5 \pm 1.00$$



# SRH Recombination Properties

## TIDLS analysis

- Determine  $E_{trap}$ ,  $k$

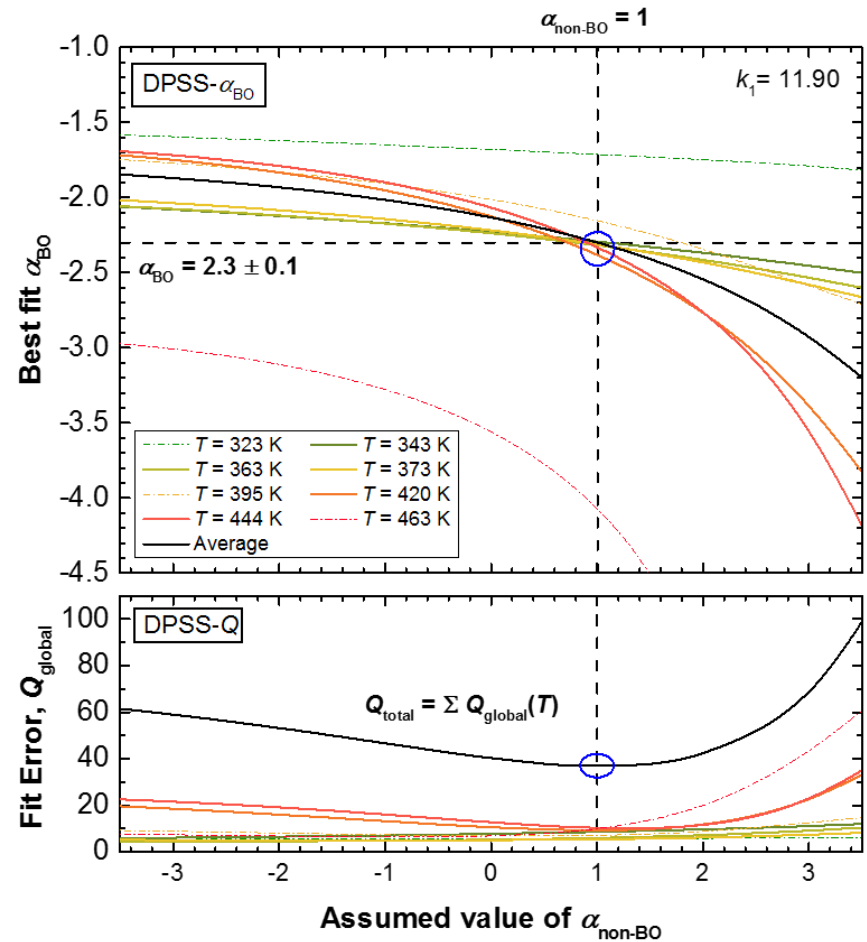
$$E_C - E_{trap} = 0.41 \pm 0.10$$

$$k_{BO} = 11.5 \pm 1.00$$

- $T$ -dependence of  $\tau_{SRH,BO}$

$$\alpha_{BO} = -2.3$$

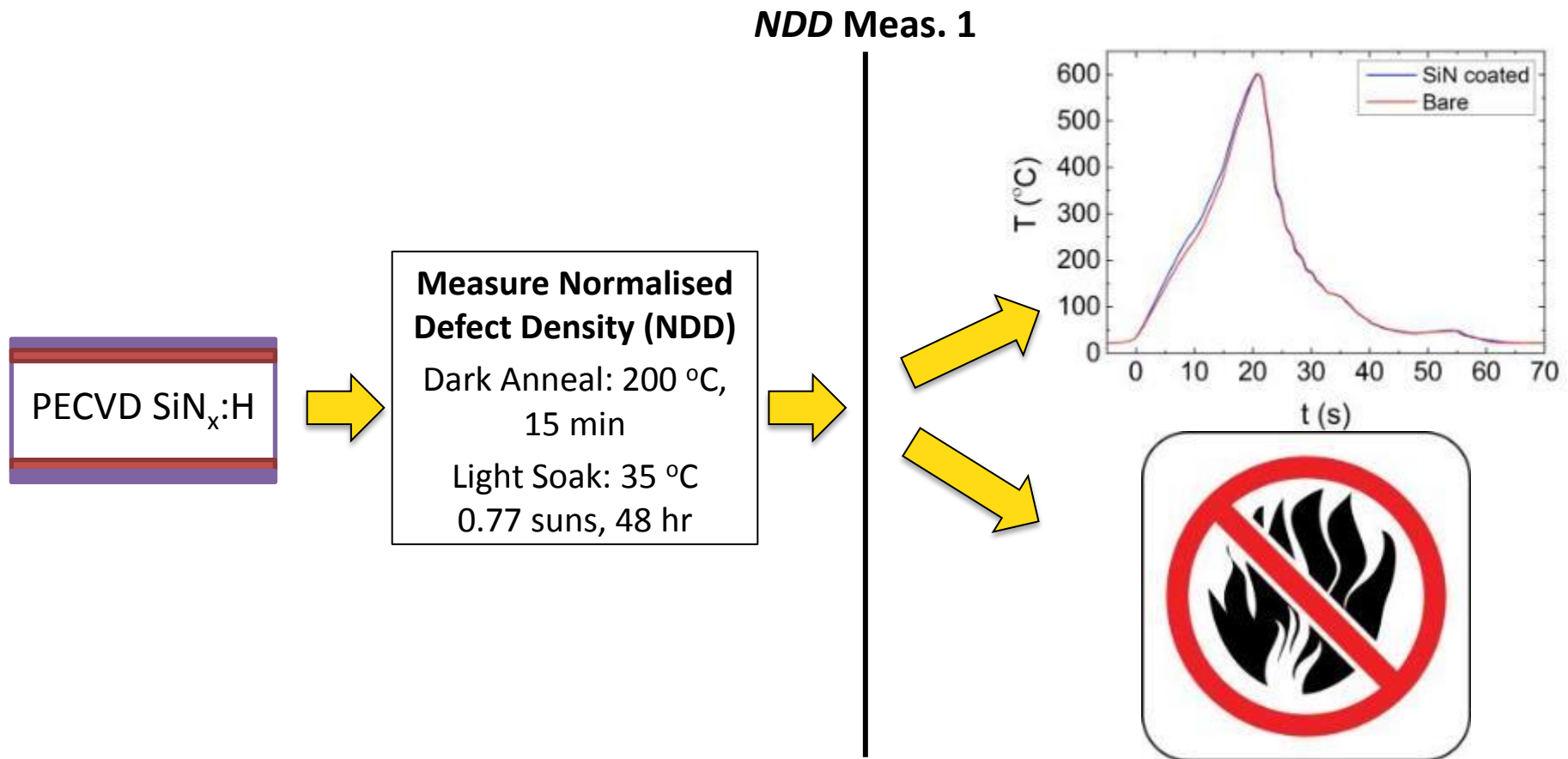
$$\sigma_{n/p}(T) \propto T^{-2.3}$$



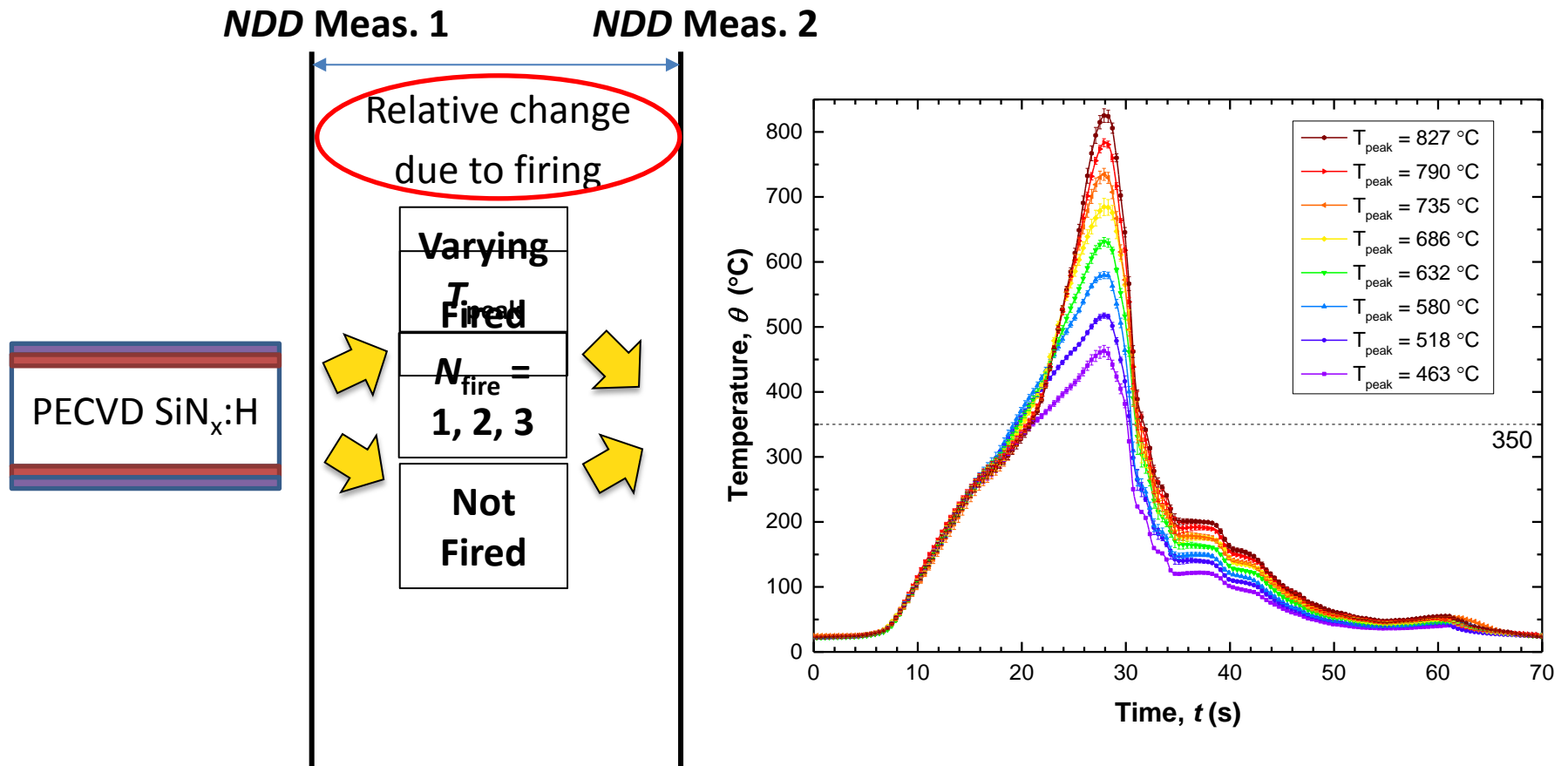
# Recombination properties of BO

- SRH properties of the BO defect (  $k$ ,  $E_{trap}$  )
- Impact of firing on  $k$
- Impact of firing on defect density

# Impact of firing – Experiment details

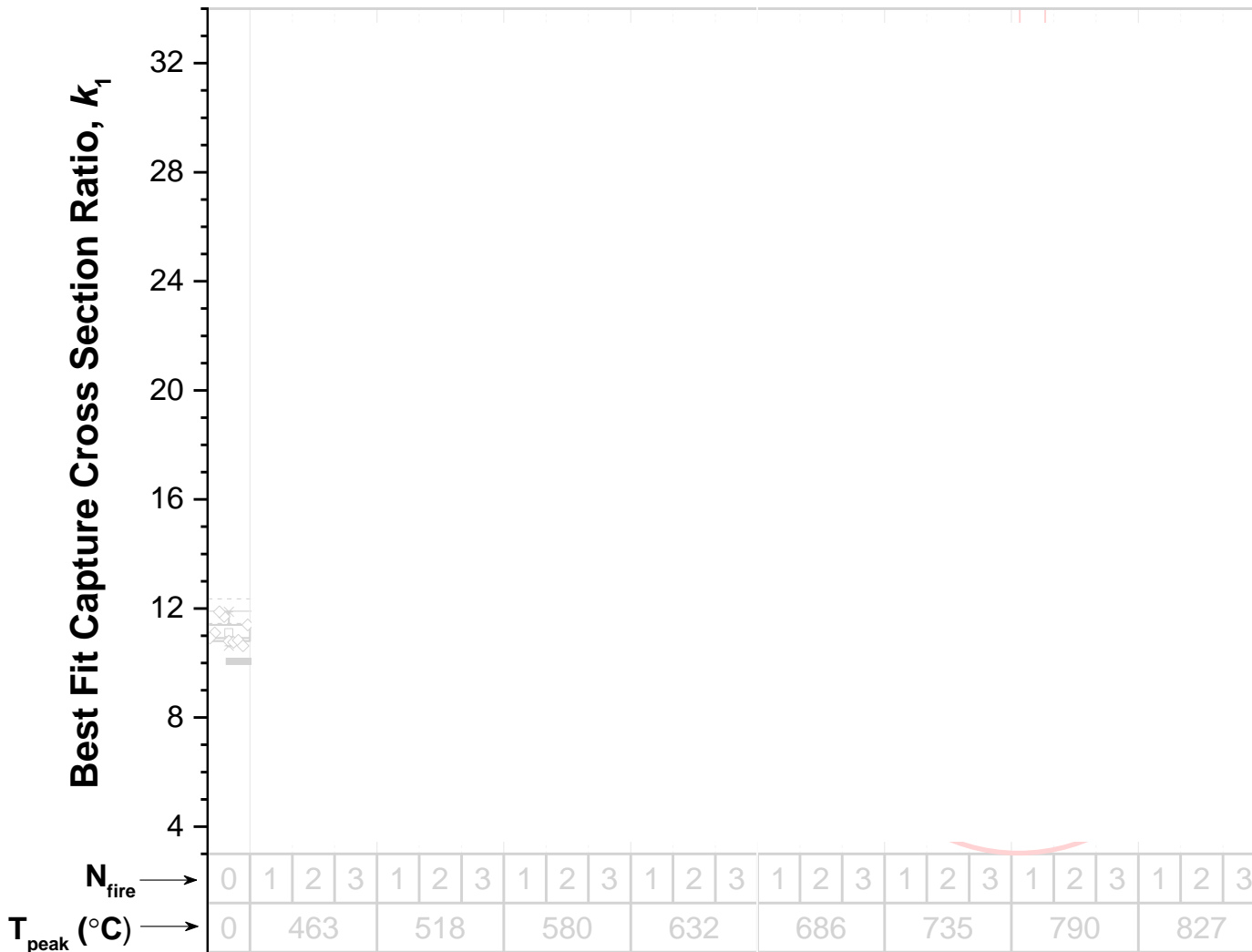


# Impact of firing – Experiment details





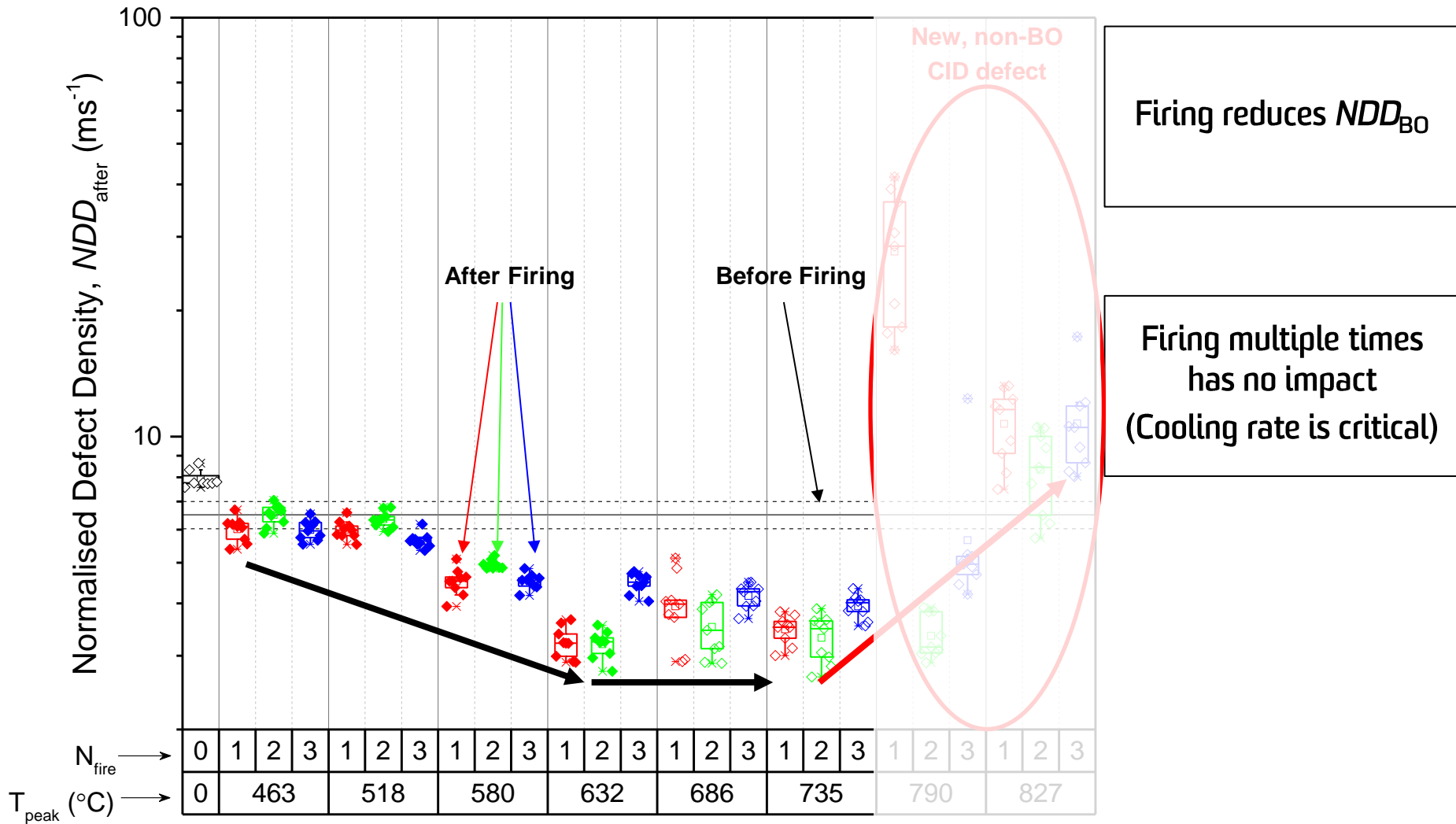
# Impact of firing on $k_{BO}$



Firing has no impact on  $k_{BO}$

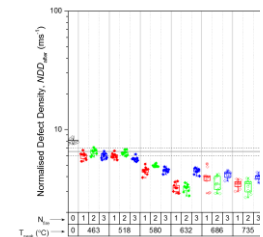
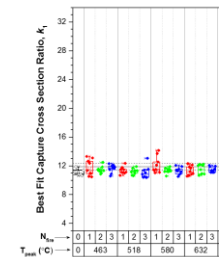
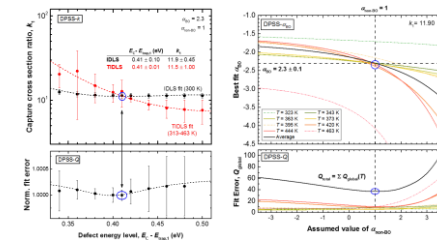
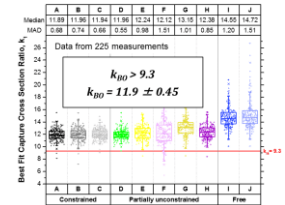
Evidence of a new CID defect in Cz silicon (firing activated)

# Impact of firing on $NDD_{BO}$



# Summary – Properties of the BO defect

- SRH properties of BO:
  - Determined  $k_{BO} = 11.9 (> 9.3)$
  - Confirmed that  $E_{trap} = E_C - 0.41$  eV
  - Determined that  $\sigma_{n/p}(T) \propto T^{-2.3}$
- Impact of firing on BO properties:
  - Confirmed that  $k_{BO}$  is not affected by firing
  - Demonstrated that firing reduces  $NDD_{BO}$
  - Firing can induce other (non-BO) CID defects in Cz silicon



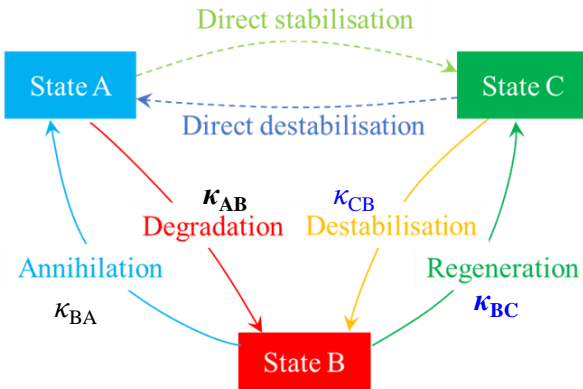


# Transition kinetics of the BO system

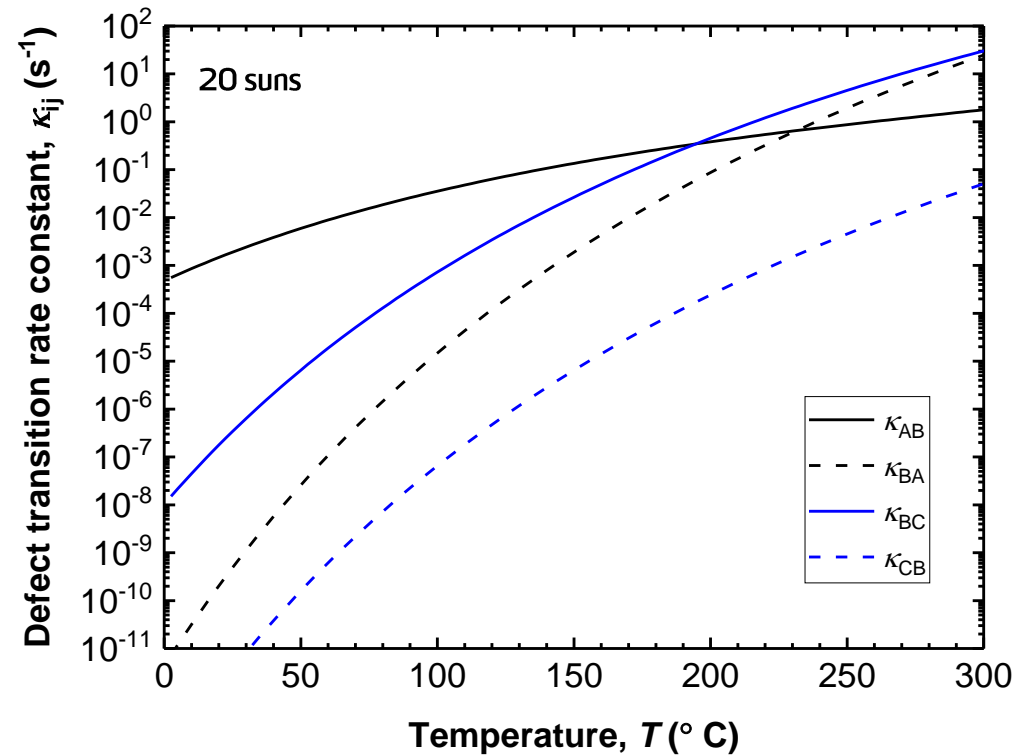
Never Stand Still

Engineering

# Transition kinetics of the BO system



Dependence of transition rates on  $T$  and illumination ( $\Delta n$ ) are of vital importance!



# Transition kinetics of the BO system

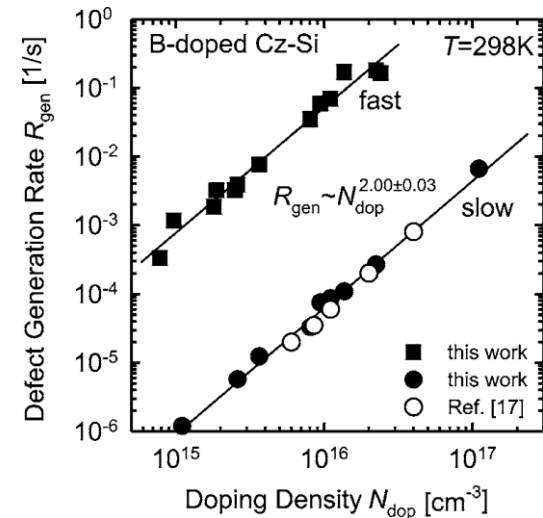
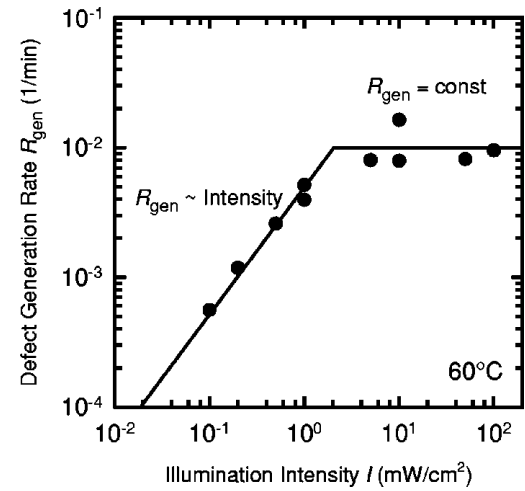
- Degradation:
  - $\kappa_{AB}$  appears to be independent of illumination intensity (>0.1 suns)
  - Other studies show  $\kappa_{deg} \propto (p_0)^2$

Which is true?

$$\kappa_{AB} \propto (p_0)^2$$

$$\kappa_{AB} \propto p \cdot p_0$$

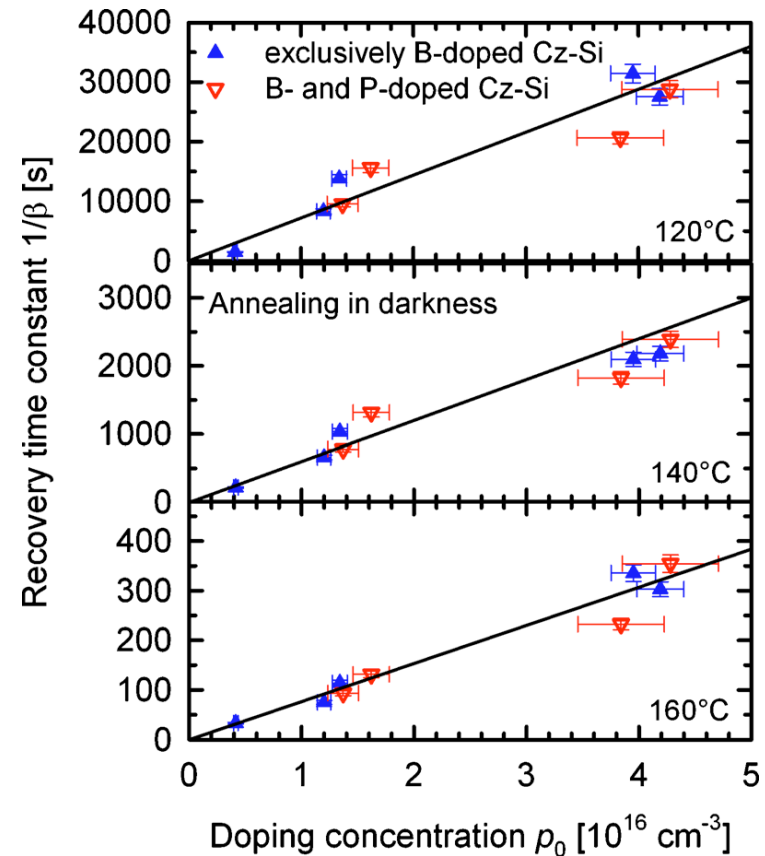
$$\kappa_{AB} \propto (p)^2$$



# Transition kinetics of the BO system

- Annealing:
  - Known to occur in dark (no carrier dependence assumed)
  - But...one study showed  $\kappa_{BA} \propto \frac{1}{p_0}$  for compensated Si

Does  $\kappa_{BA}$  have a carrier dependence?



# Issue with reaction rate studies

- **Process  $T \neq$  Measurement  $T$ !**

Required parameters

$$p(T) = p_o(T) + \Delta p(T)$$

$$G(T) = \frac{\Delta n(T)}{\tau_{eff}(T, \Delta n)}$$

Measured parameters

$$p(300K) = p_o(300K) + \Delta p(300K)$$

$$G(300K) = \frac{\Delta n(300K)}{\tau_{eff}(300K, \Delta n)}$$

**Need a method to determine  $\Delta n(T)$   
from  $\tau_{eff}(300K)$  and  $G(300K)$**

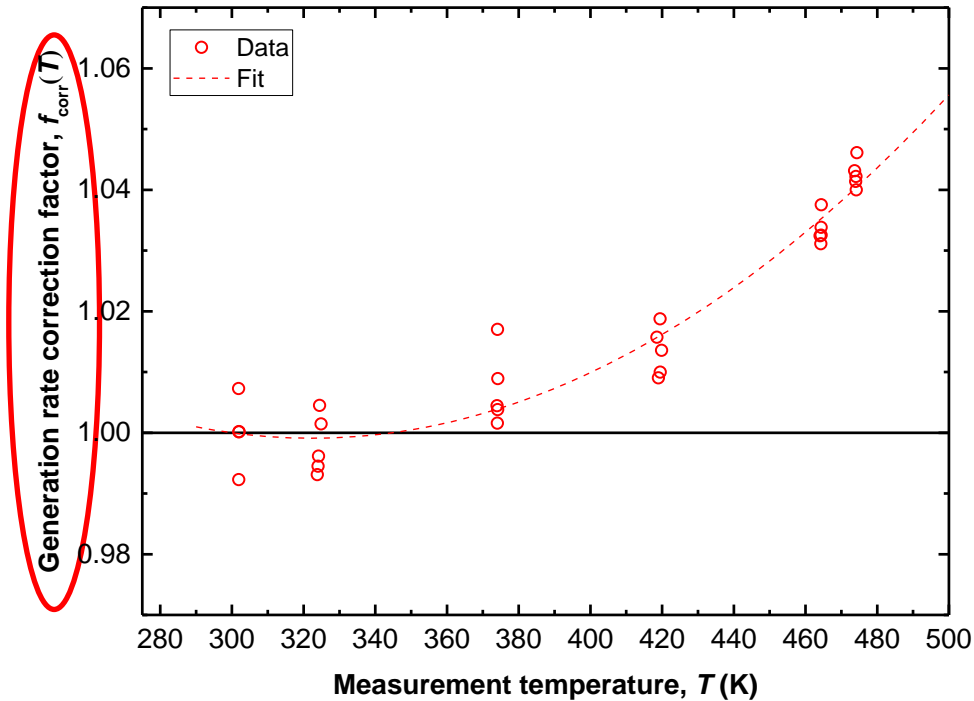


# Reaction kinetics of the BO system

- Model to obtain  $\tau_{\text{eff}}(T)$  from  $\tau_{\text{eff}}(300\text{ K})$
- Temporary deactivation (annealing) kinetics
- Degradation kinetics

# Temperature dependence of lifetime

$$G(T) = \frac{\Delta n(T)}{\tau_{eff}(T, \Delta n)}$$



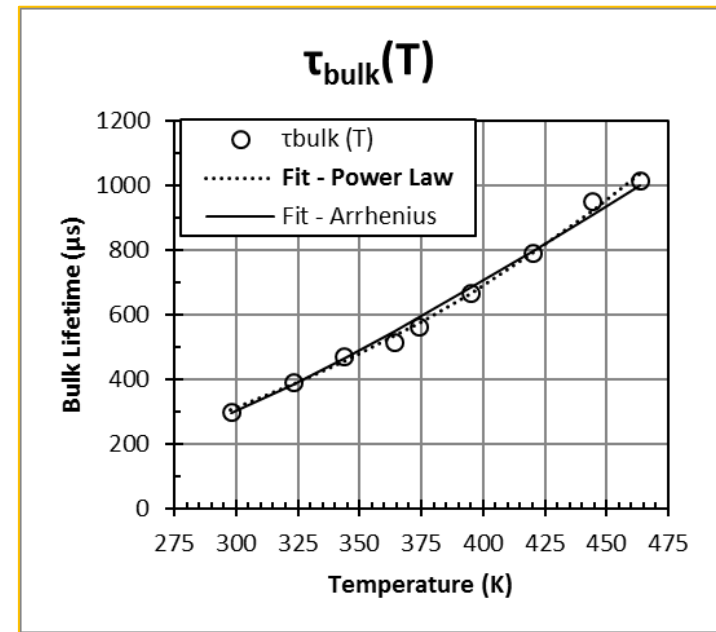
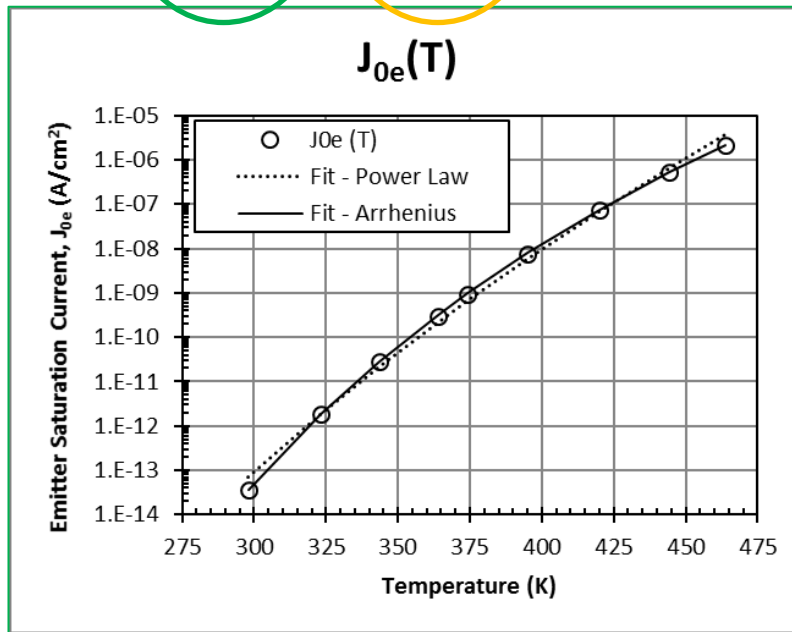
# Temperature dependence of lifetime

$$G(T) = \frac{\Delta n(T)}{\tau_{eff}(T, \Delta n)}$$

$$\frac{1}{\tau_{DA}(T, \Delta n)} = \frac{1}{\tau_{surf}(T, \Delta n)} + \frac{1}{\tau_{bulk, fixed}(T)} + \frac{1}{\tau_{SRH, non-BO}(T)}$$

$$\frac{1}{\tau_{LS}(T, \Delta n)} = \frac{1}{\tau_{surf}(T, \Delta n)} + \frac{1}{\tau_{bulk, fixed}(T)} + \frac{1}{\tau_{SRH, non-BO}(T)} + \frac{1}{\tau_{SRH, BO}(T, \Delta n)}$$

Step 1: Fit  $\tau_{DA}(T, \Delta n)$  and  $\tau_{LS}(T, \Delta n)$  at each temperature



# Temperature dependence of lifetime

$$G(T) = \frac{\Delta n(T)}{\tau_{eff}(T, \Delta n)}$$

$$\frac{1}{\tau_{DA}(T, \Delta n)} = \frac{1}{\tau_{surf}(T, \Delta n)} + \frac{1}{\tau_{bulk, fixed}(T)} + \frac{1}{\tau_{SRH, non-BO}(T)}$$

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$$\downarrow$$

$$\tau_{n0, BO}(T)$$

$$\tau_{n0, non-BO}(T)$$

$$\tau_{bulk, fixed}(T)$$

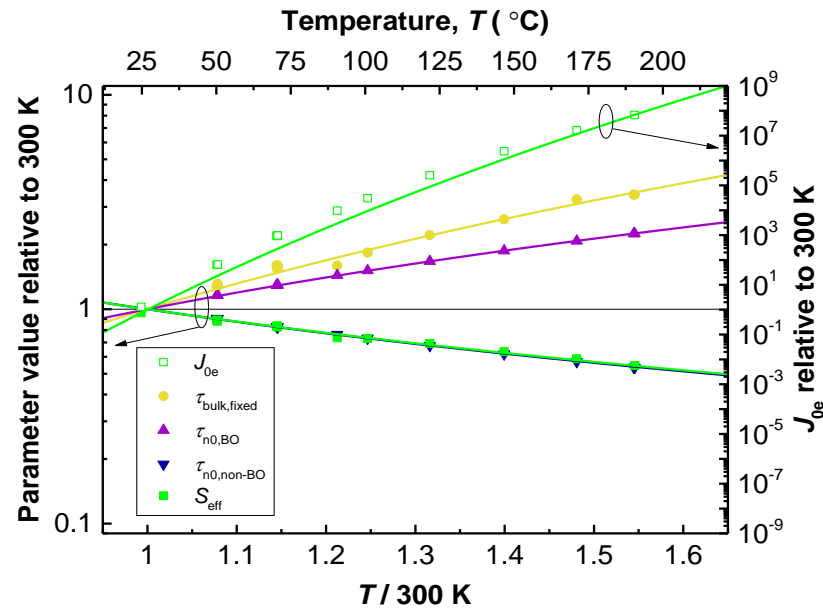
$$\frac{1}{\tau_{surf}(T, \Delta n)}$$

$$\frac{1}{\tau_{surf}(T, \Delta n)}$$

Step 2: Apply this relation for each fitted parameter:

$$Param(T) = Param(300K) \times \left(\frac{T}{300}\right)^{\alpha_{param}}$$

# Temperature dependence of lifetime



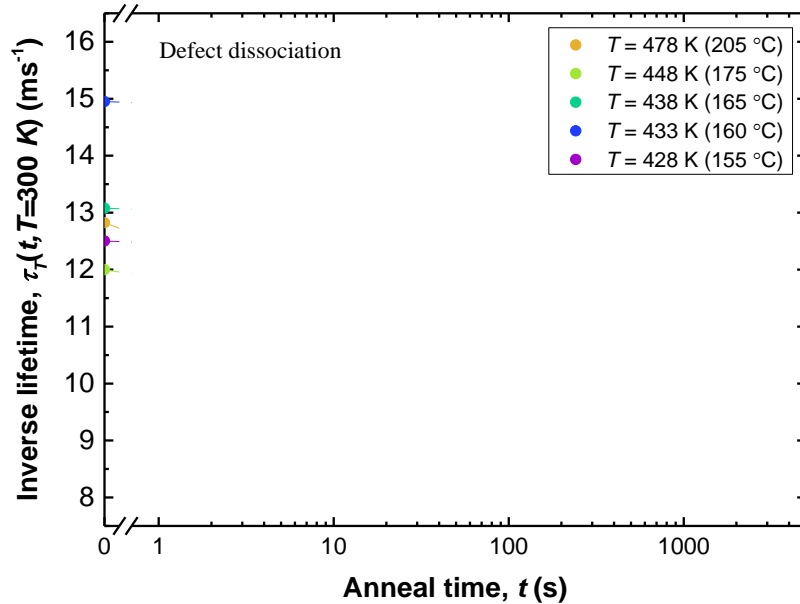
Parameter	Relevant lifetime component	Exponent of temperature dependence	Value for $\alpha_{\text{param}}$
$\tau_{\text{bulk, fixed}}^*$	$\tau_{\text{bulk, fixed}}(T)$	$\alpha_b$	$2.880 \pm 0.032$
$S_{\text{eff}}$	$\tau_{\text{surf}}(T)$	$\alpha_{S_{\text{eff}}}$	$-1.395 \pm 0.030$
$J_{0e}$	$\tau_{\text{surf}}(T)$	$\alpha_{J_{0e}}$	$41.449 \pm 0.044$
$\tau_{n0, \text{BO}}$	$\tau_{\text{SRH, BO}}(T)$	$\alpha_{n0, \text{BO}}$	$1.870 \pm 0.003$
$\tau_{n0, \text{non-BO}}^*$	$\tau_{\text{SRH, non-BO}}(T)$	$\alpha_{n0, \text{non-BO}}$	$-1.420 \pm 0.006$

\* may be specific to wafers used in this study

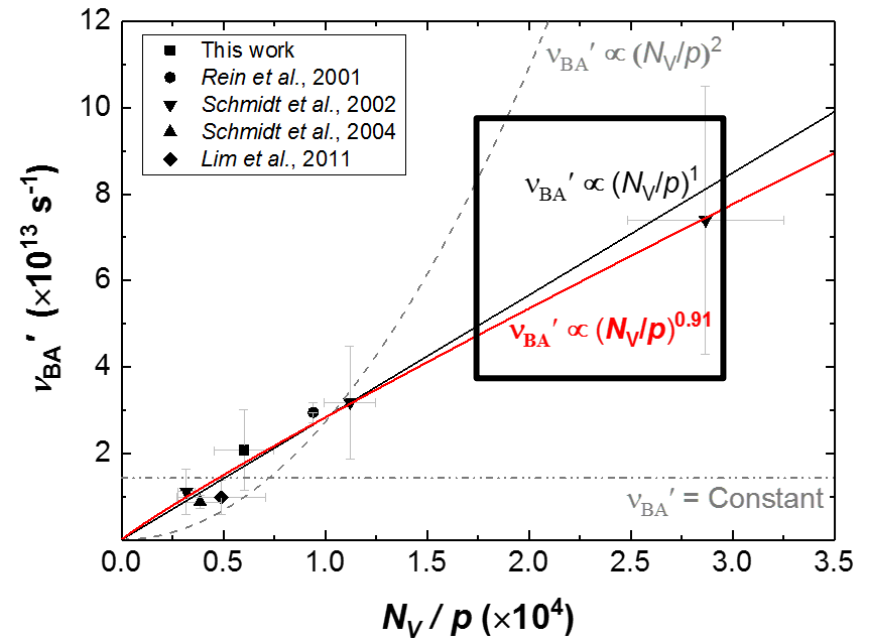
# Reaction kinetics of the BO system

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- Temporary deactivation (annealing) kinetics
- Degradation kinetics

# Annealing kinetics

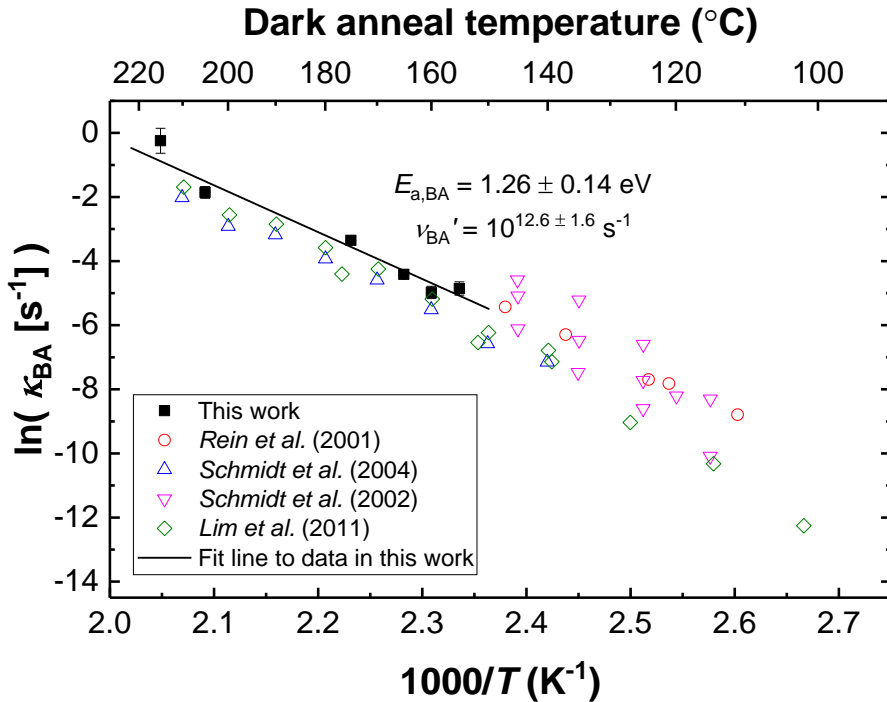


Rates extracted

$$\kappa_{\text{BA}} \propto \left[ \frac{1}{p(T)} \right]$$


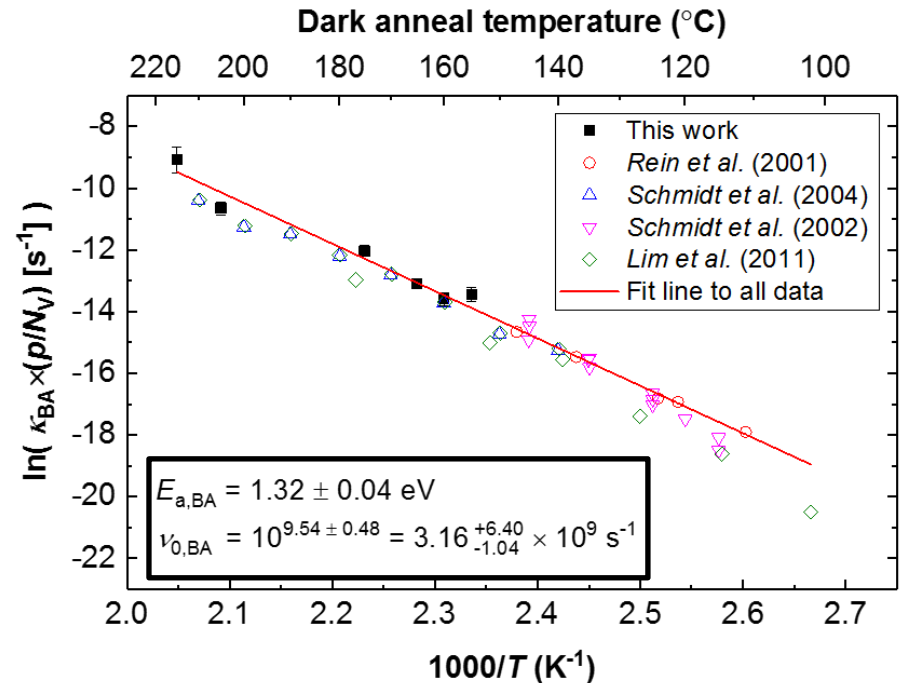
# Annealing kinetics

$\kappa_{BA}$  - not normalised



$$\kappa_{BA} = \nu_{BA}' \cdot e^{\frac{-E_{a,BA}}{k_B T}}$$

$\kappa_{BA}$  - normalised to  $(p/N_V)^{-1}$



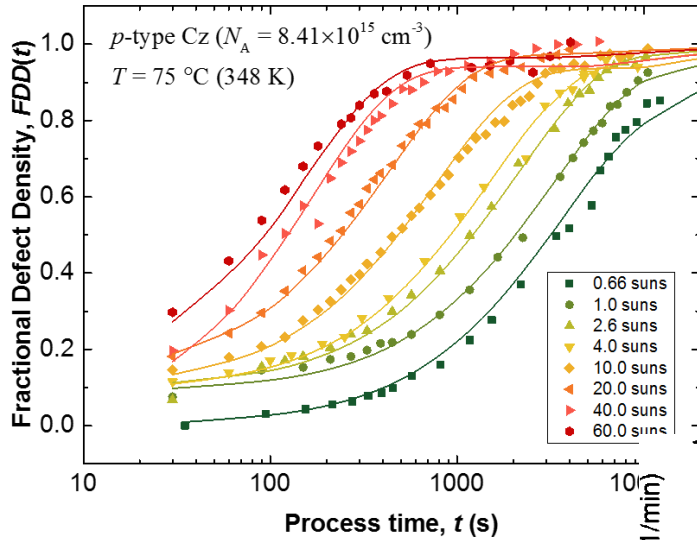
$$\kappa_{BA} = \nu_{0,BA} \cdot \left[ \frac{N_C(T)}{p(T)} \right] \cdot e^{\frac{-E_{a,BA}}{k_B T}}$$



# Reaction kinetics of the BO system

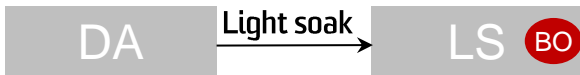
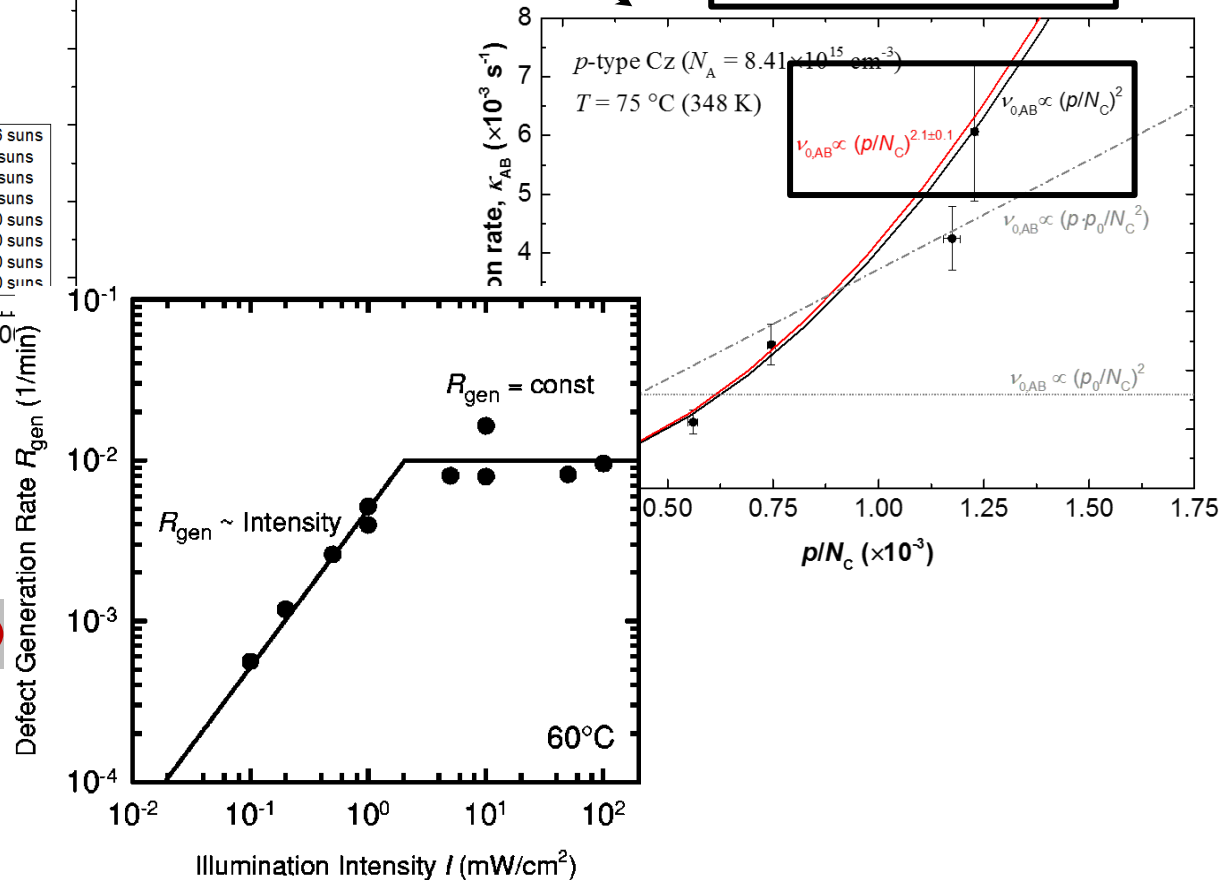
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# Degradation kinetics



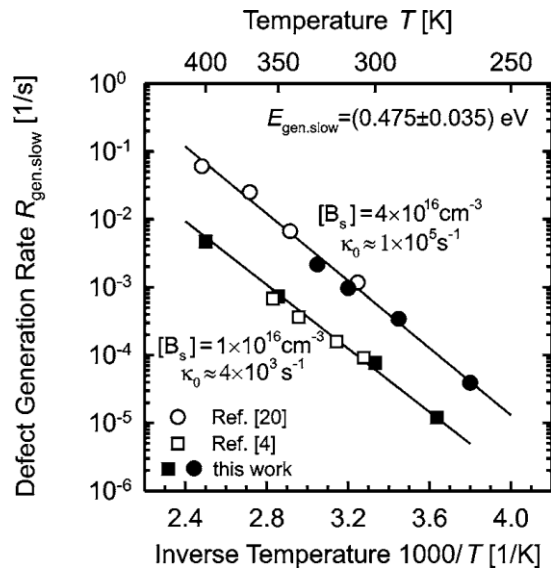
Rates extracted

$$\kappa_{AB} \propto [p(T)]^2$$



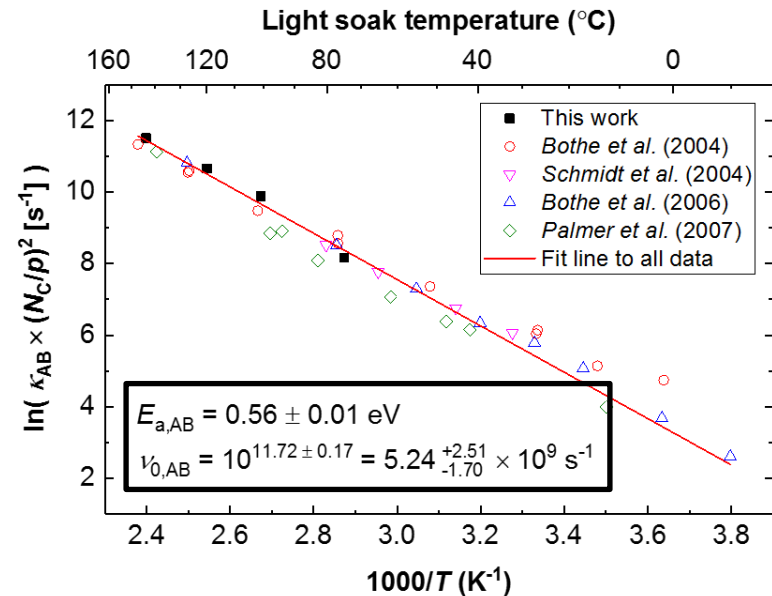
# Degradation kinetics

$\kappa_{AB}$  - not normalised  
(Bothe and Schmidt, 2004)



$$\kappa_{AB} = \nu_{AB}' \cdot e^{-\frac{E_{a,AB}}{k_B T}}$$

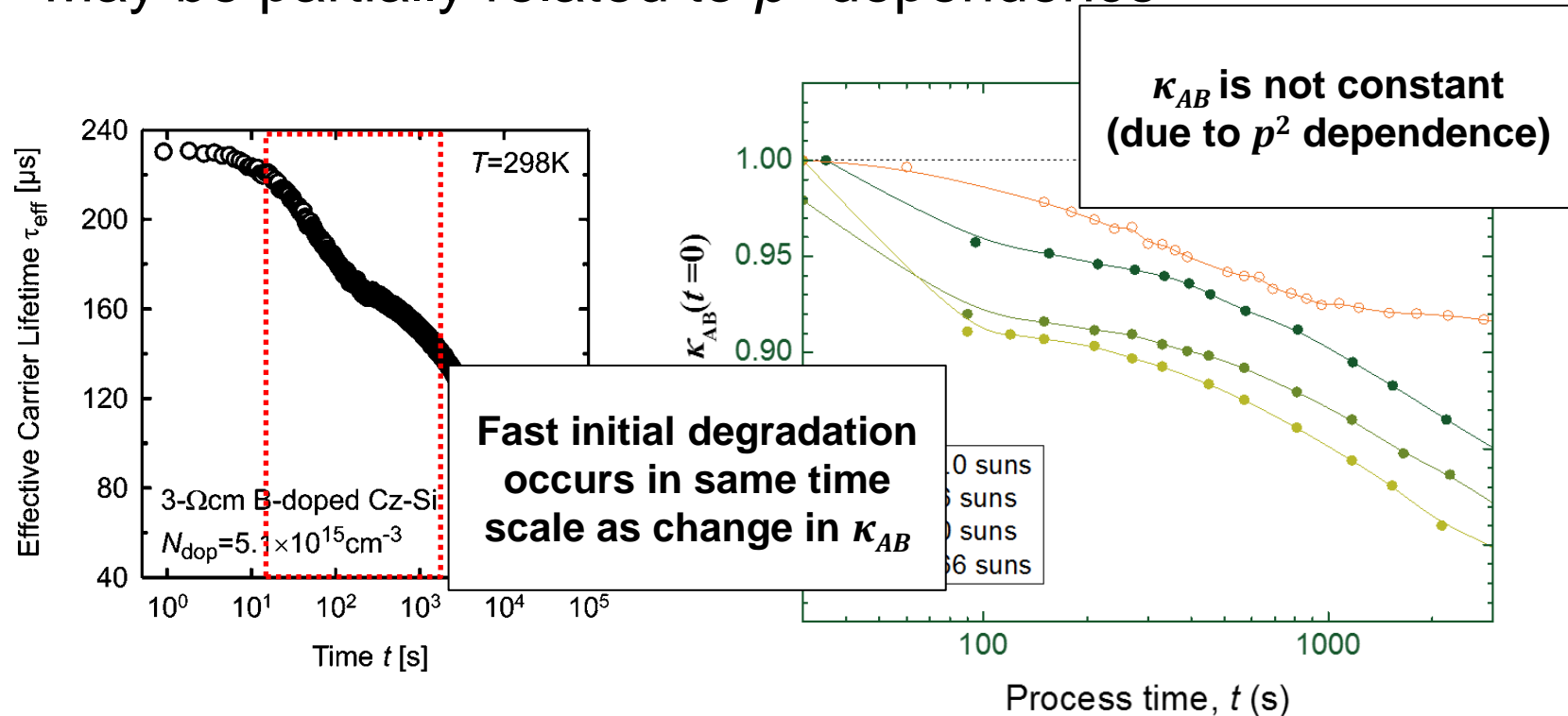
$\kappa_{AB}$  - normalised to  $(p/N_C)^2$   
(This work)



$$\kappa_{AB} = \nu_{0,AB} \cdot \left[ \frac{p(T)}{N_C(T)} \right]^2 \cdot e^{-\frac{E_{a,AB}}{k_B T}}$$

# Implications of degradation kinetics

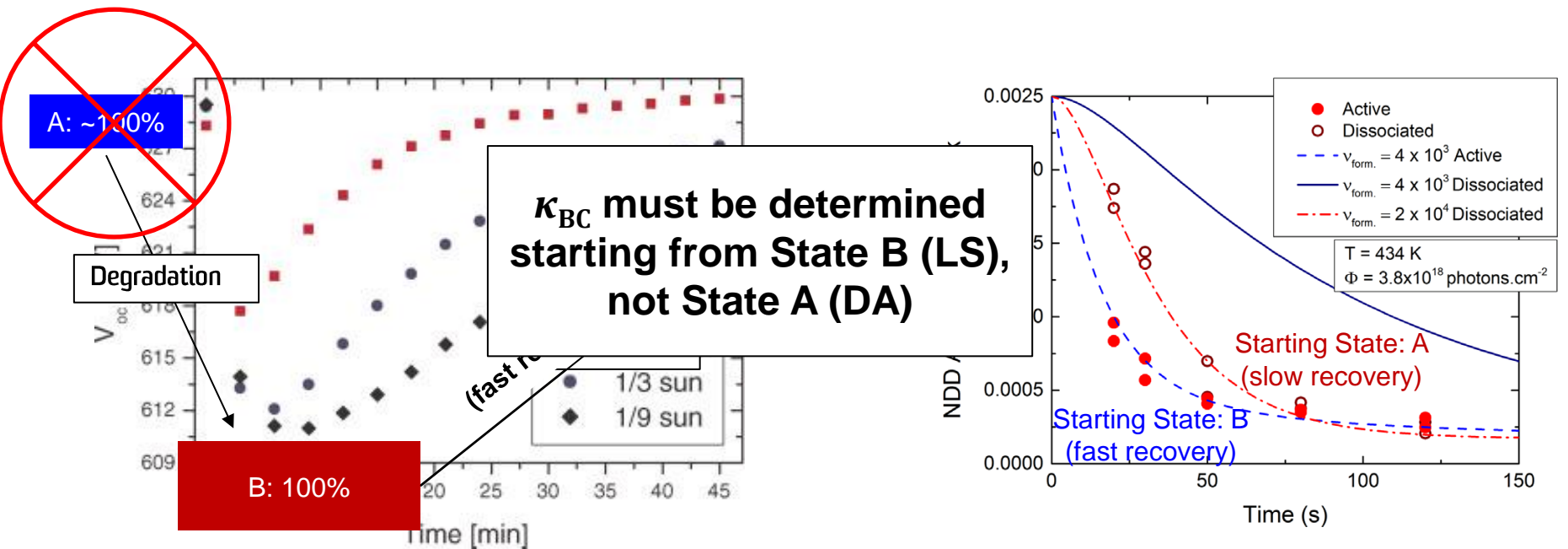
- Fast initial degradation (“FRC”)
  - May be partially related to  $p^2$  dependence



# Implications of degradation kinetics

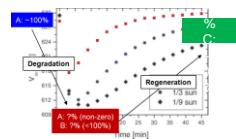
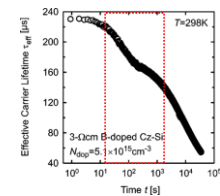
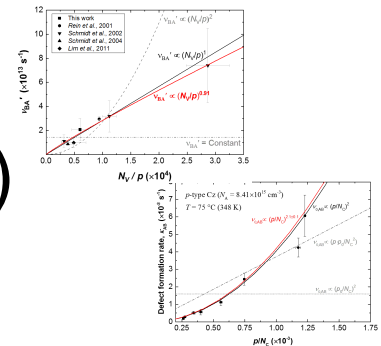
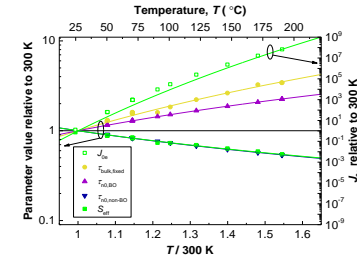
- Regeneration rates

- Regen ( $B \rightarrow C$ ) occurs only after degradation ( $A \rightarrow B$ )
- $\kappa_{BC}$  will be limited by  $\kappa_{AB}$



# Summary – Reaction Kinetics

- Developed parameterization to obtain  $\tau_{\text{eff}}(T)$  from  $\tau_{\text{eff}}(300\text{ K})$
- Carrier dependence confirmed for annealing ( $A \rightarrow B$ ), degradation ( $B \rightarrow A$ )
- Carrier dependence explains other observed kinetics phenomena



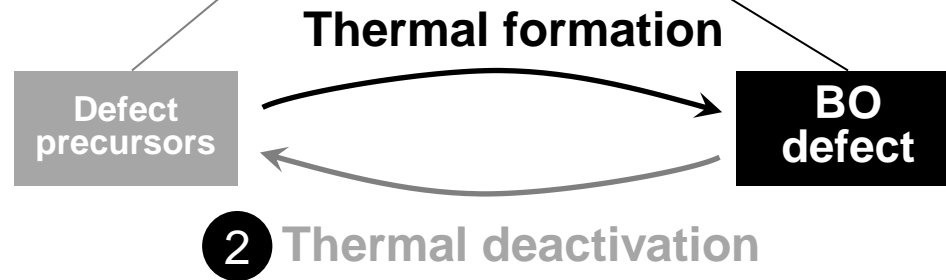
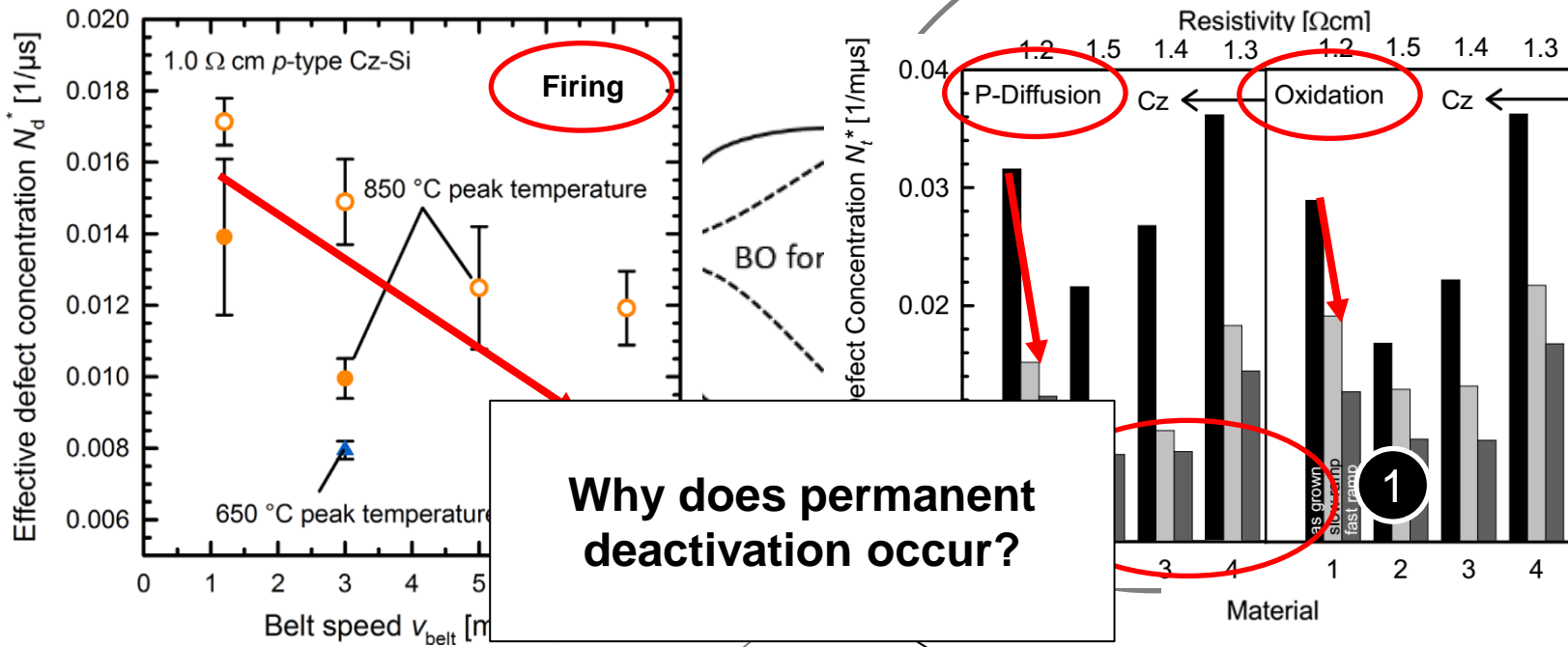


# Mechanisms for permanent deactivation of BO defects

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# Permanent deactivation

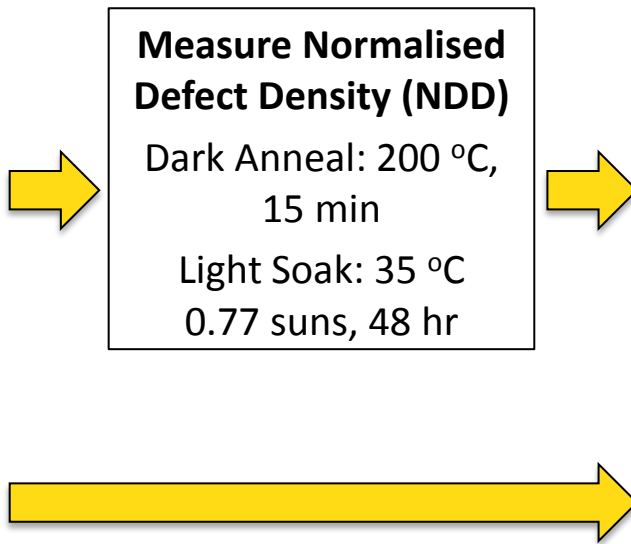
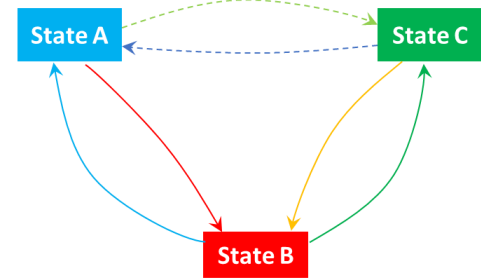




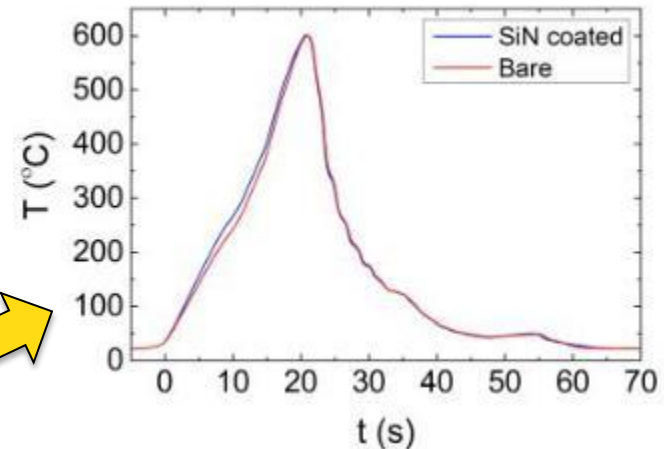
# Deactivation mechanisms

- Why does regeneration occur?
- Why does thermal deactivation occur?
- Are they related?

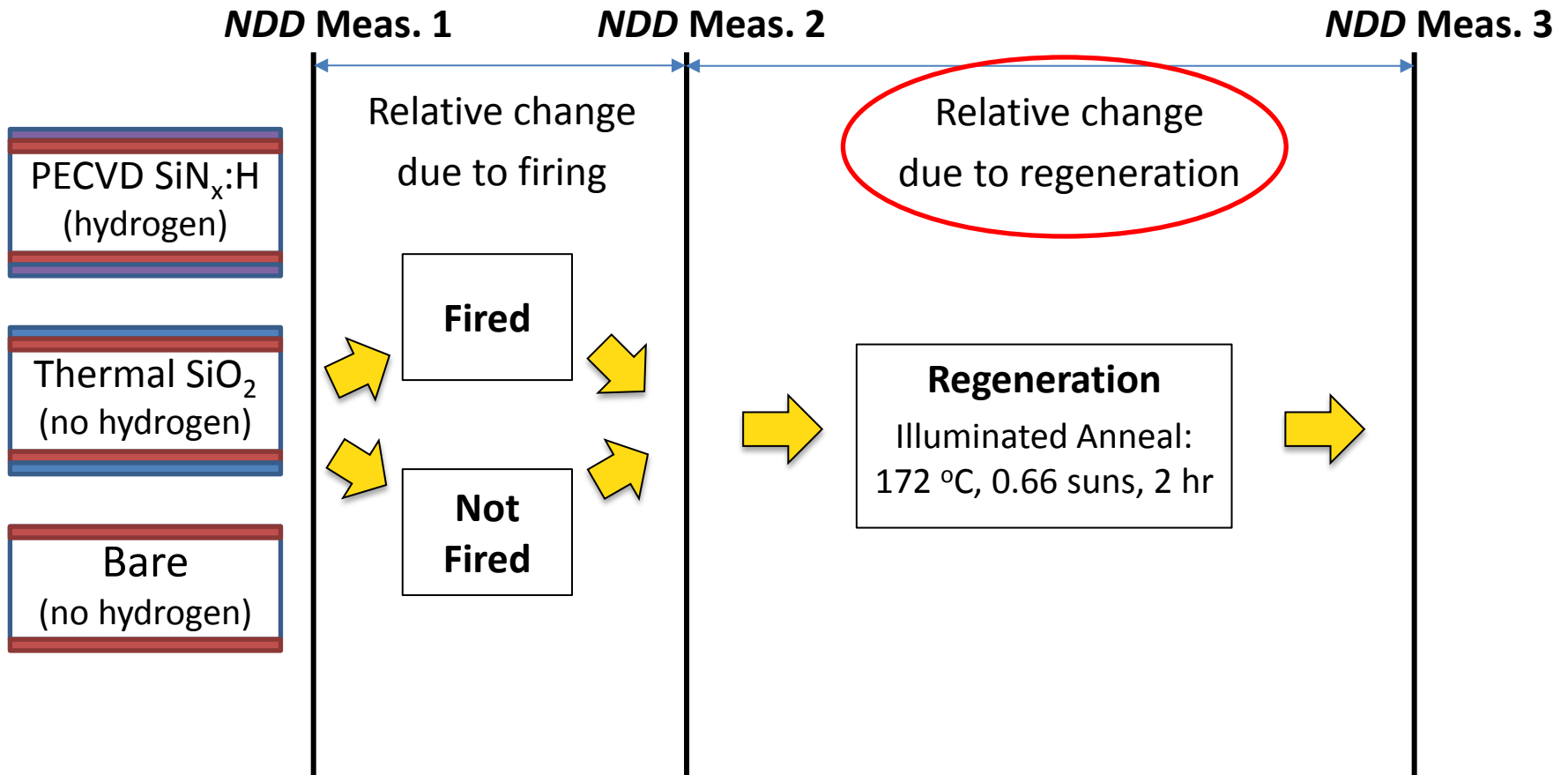
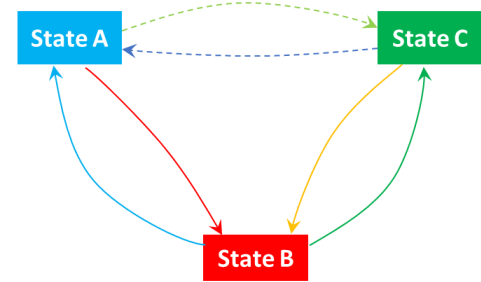
# Experimental Details



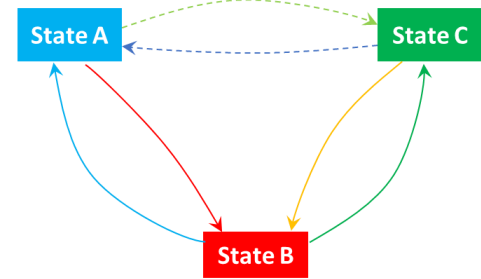
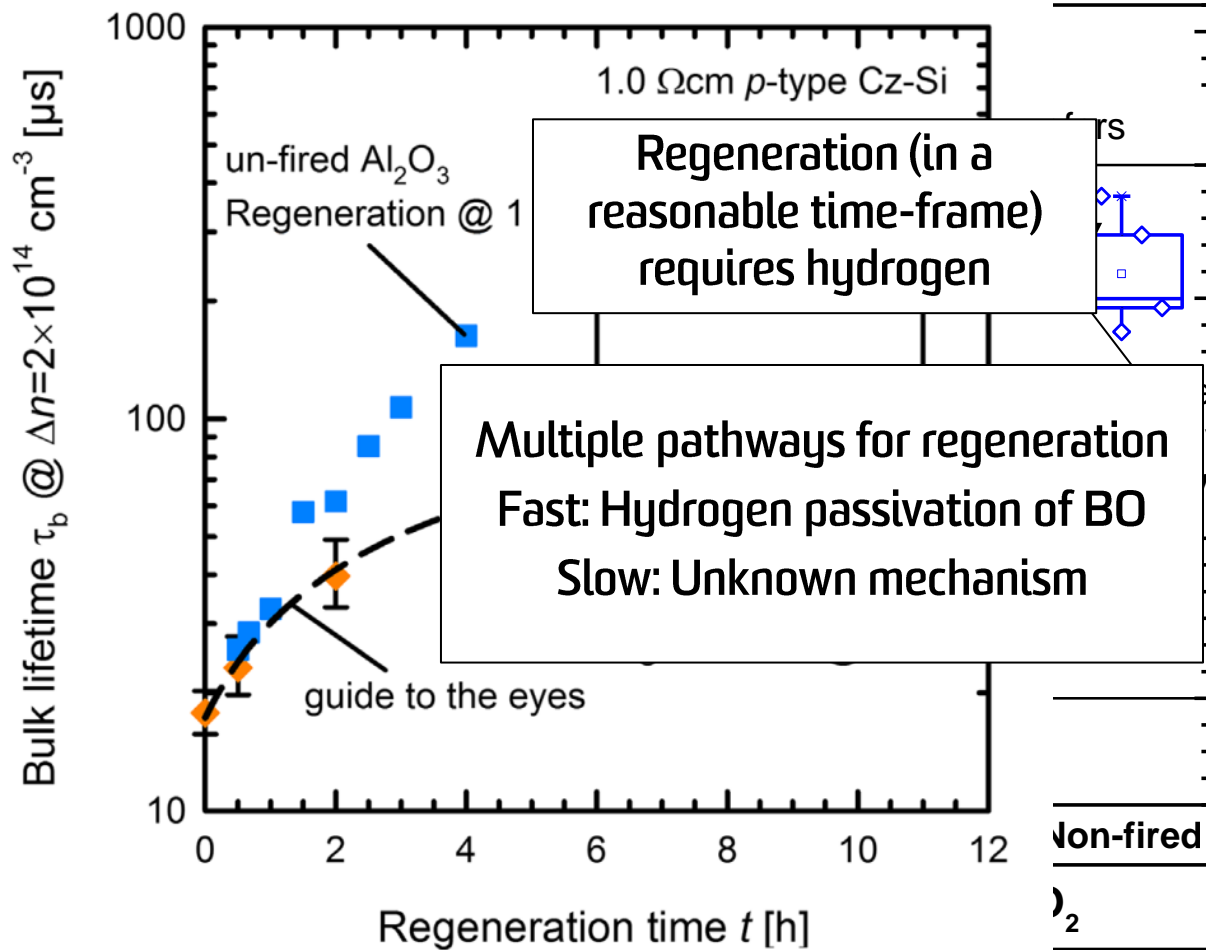
## NDD Meas. 1



# Regeneration



# Regeneration

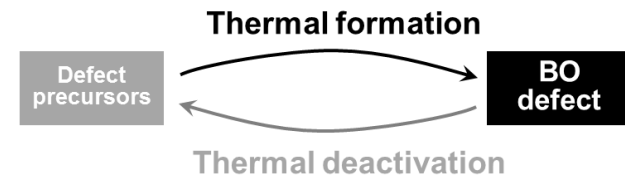


Regeneration observed in hydrogen-lean samples (very long time scales)

# Deactivation mechanisms

- Why does regeneration occur?
- Why does thermal deactivation occur?
- Are they related?

# Thermal deactivation



**NDD Meas. 1**

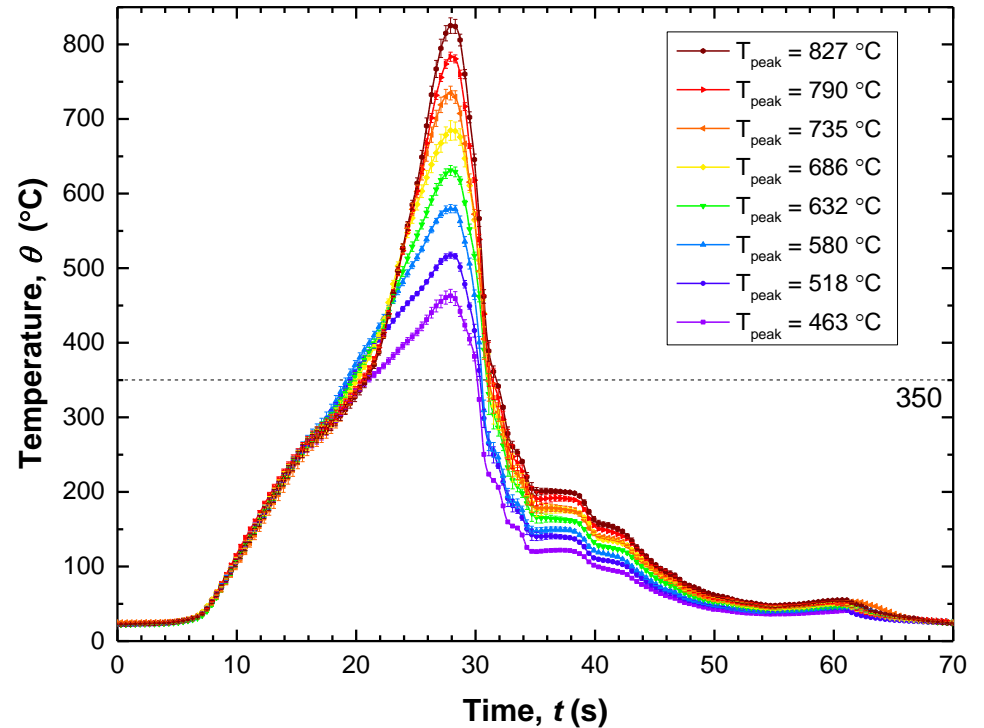
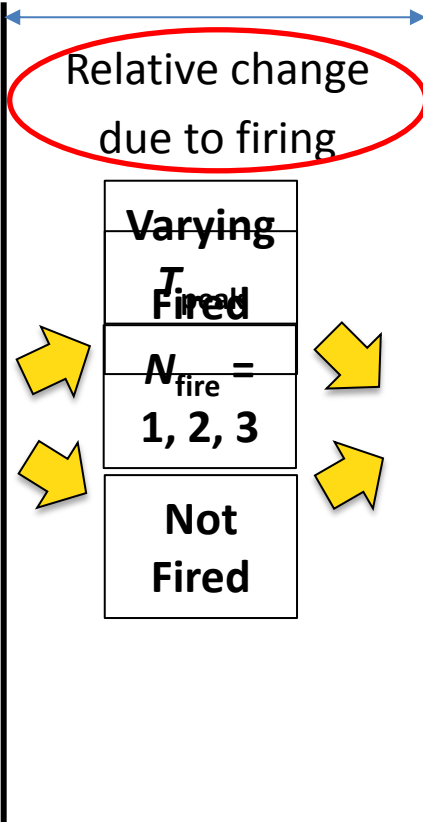
**NDD Meas. 2**

*NDD Meas. 3*

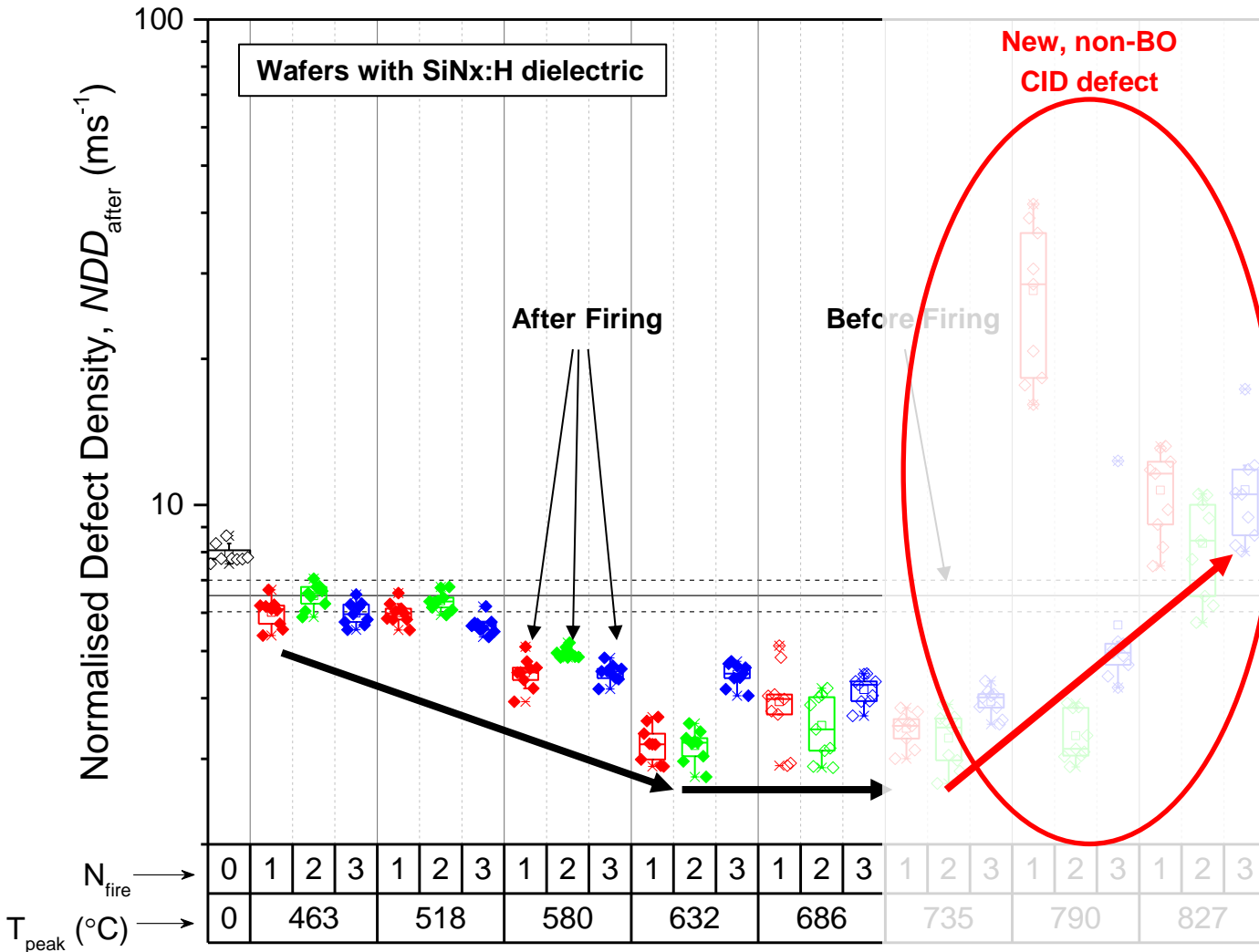
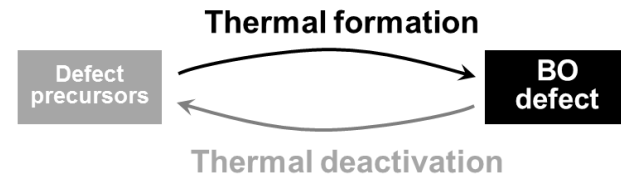
PECVD SiN<sub>x</sub>:H  
(hydrogen)

Thermal SiO<sub>2</sub>  
(no hydrogen)

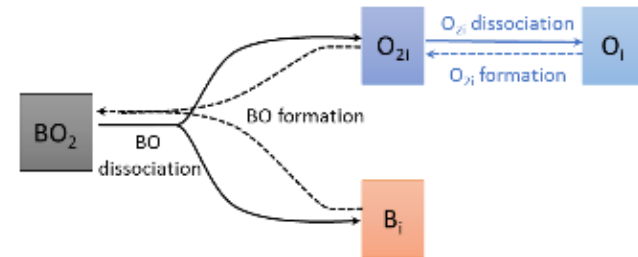
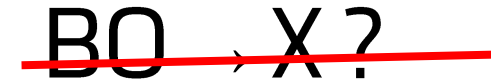
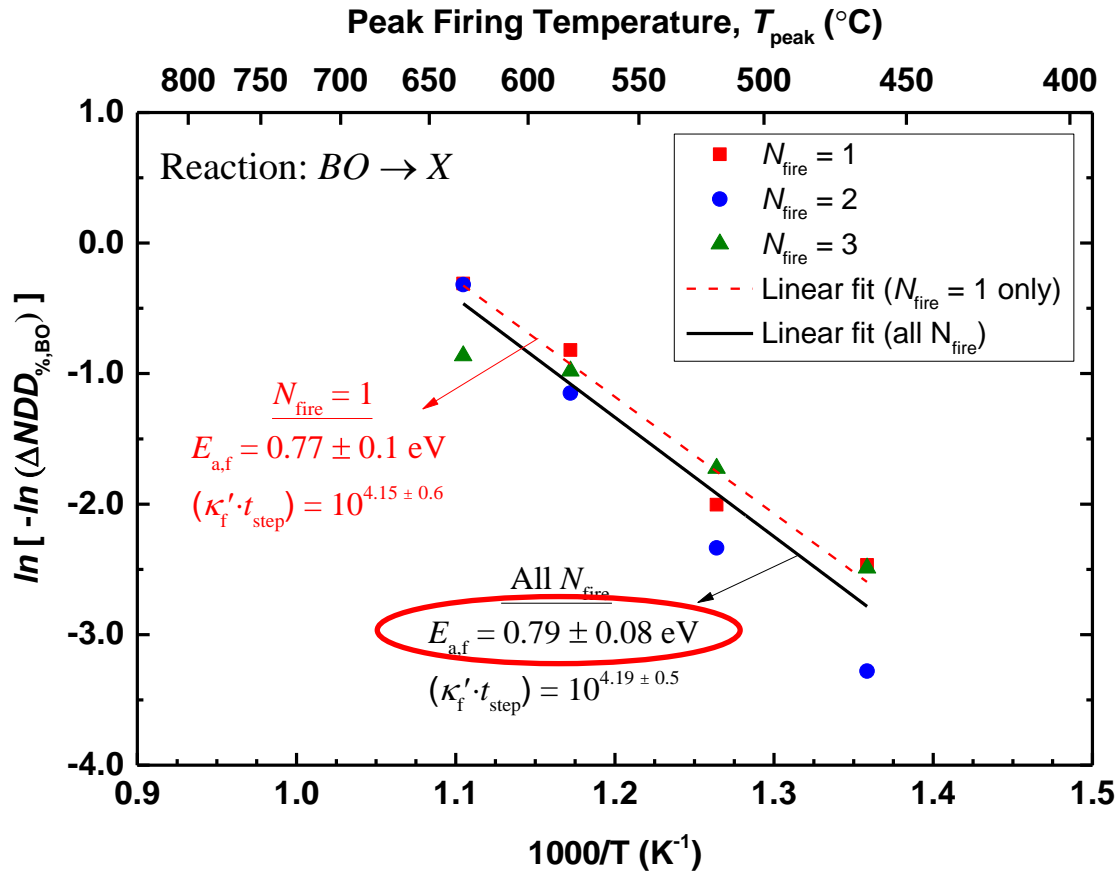
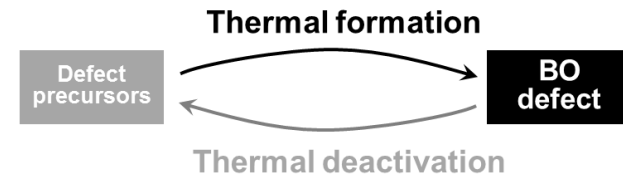
Bare  
(no hydrogen)



# Thermal deactivation

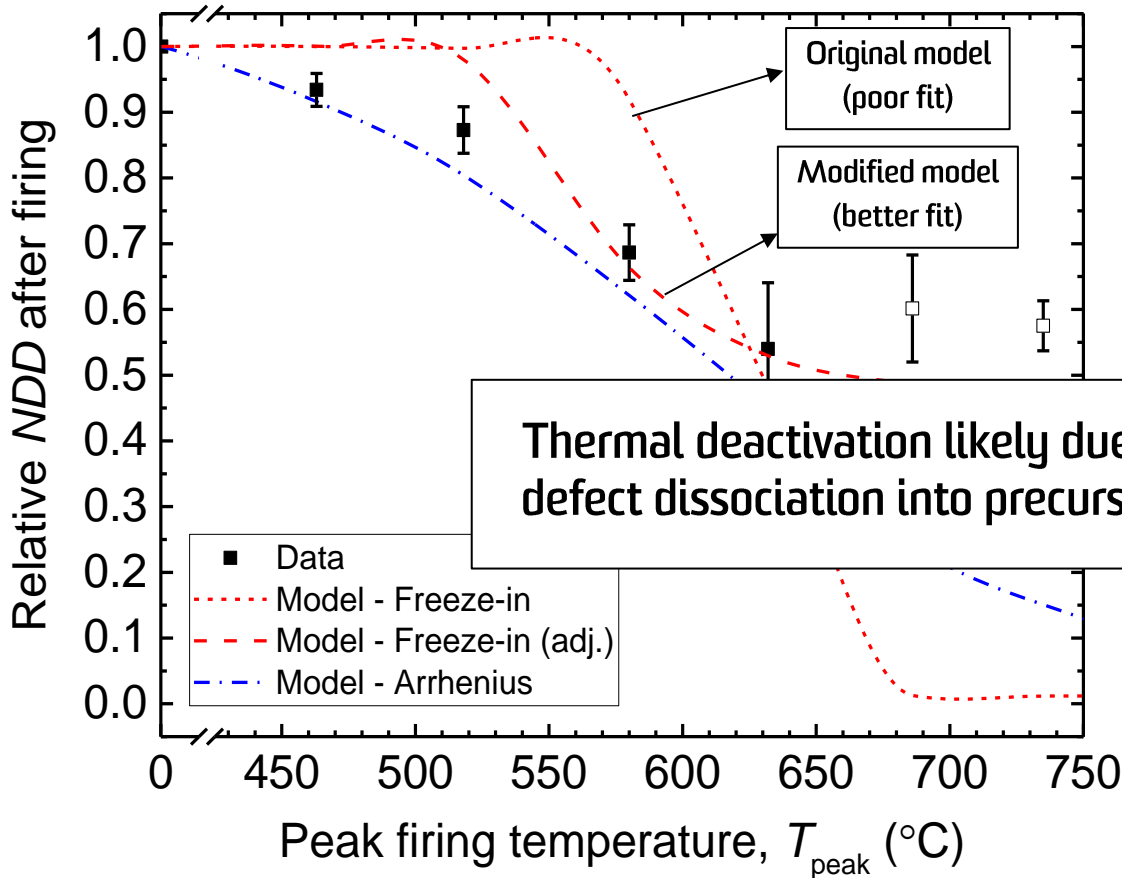
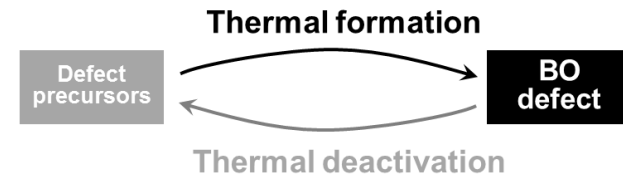


# Thermal deactivation

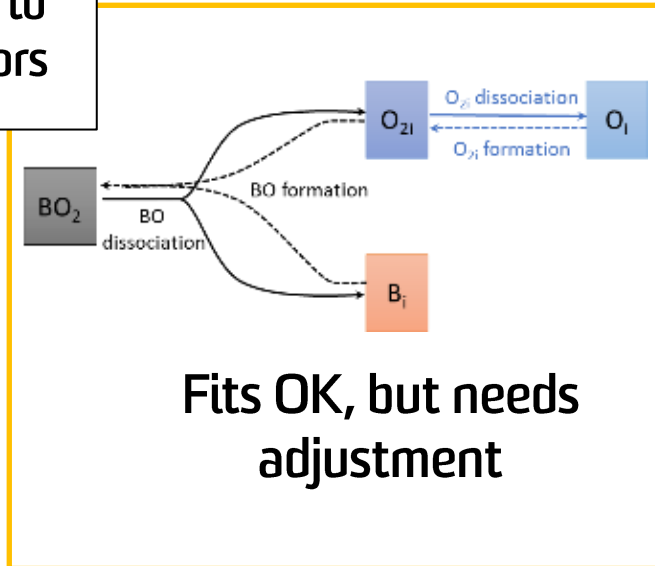




# Thermal deactivation



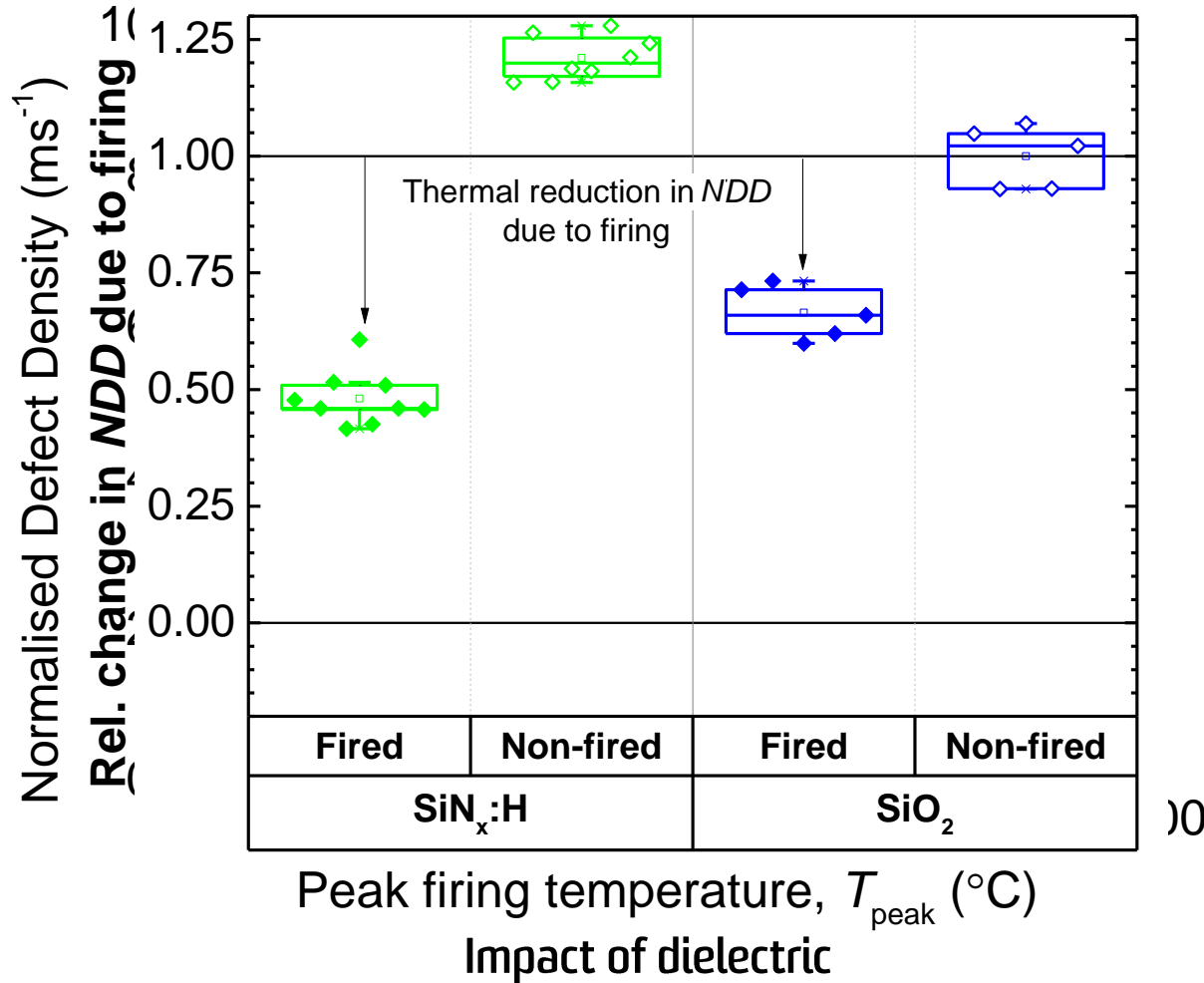
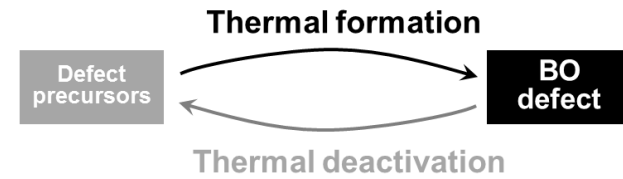
~~BO~~ → X?



# Deactivation mechanisms

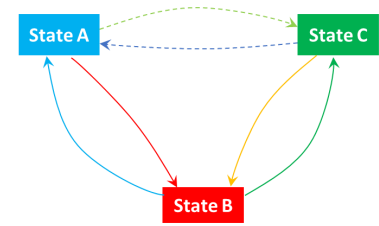
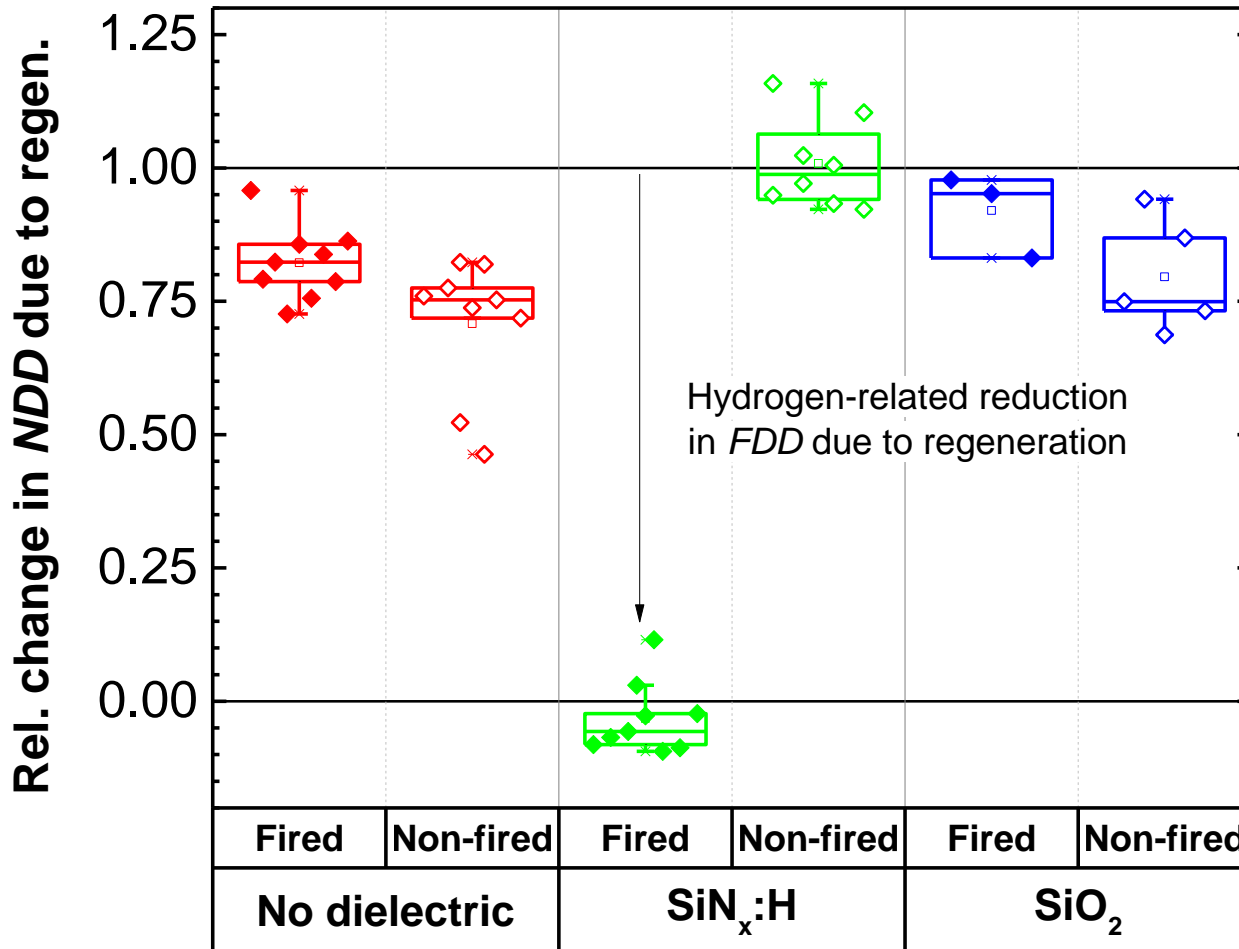
- Why does regeneration occur?
- Why does thermal deactivation occur?
- Are they related?

# Thermal deactivation



Similar thermal reduction in oxide & nitride passivated samples (i.e. Thermal deactivation is not hydrogen-related)

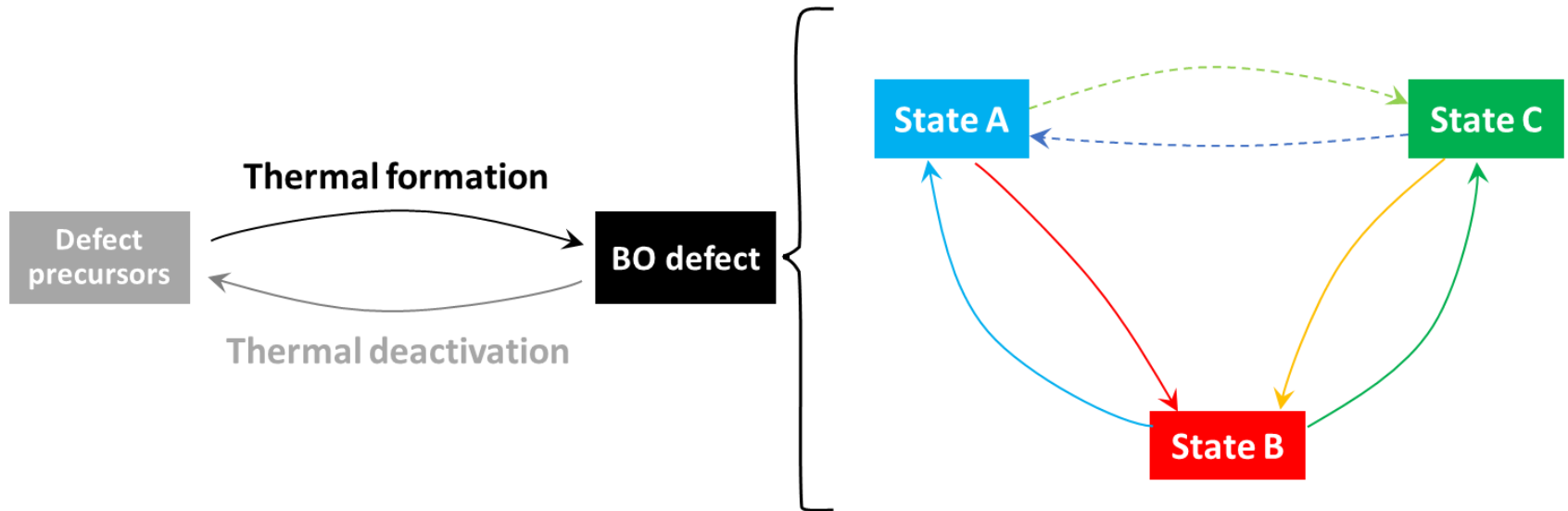
# Regeneration



Similar thermal reduction in oxide & nitride passivated samples  
(i.e. Thermal deactivation is not hydrogen-related)

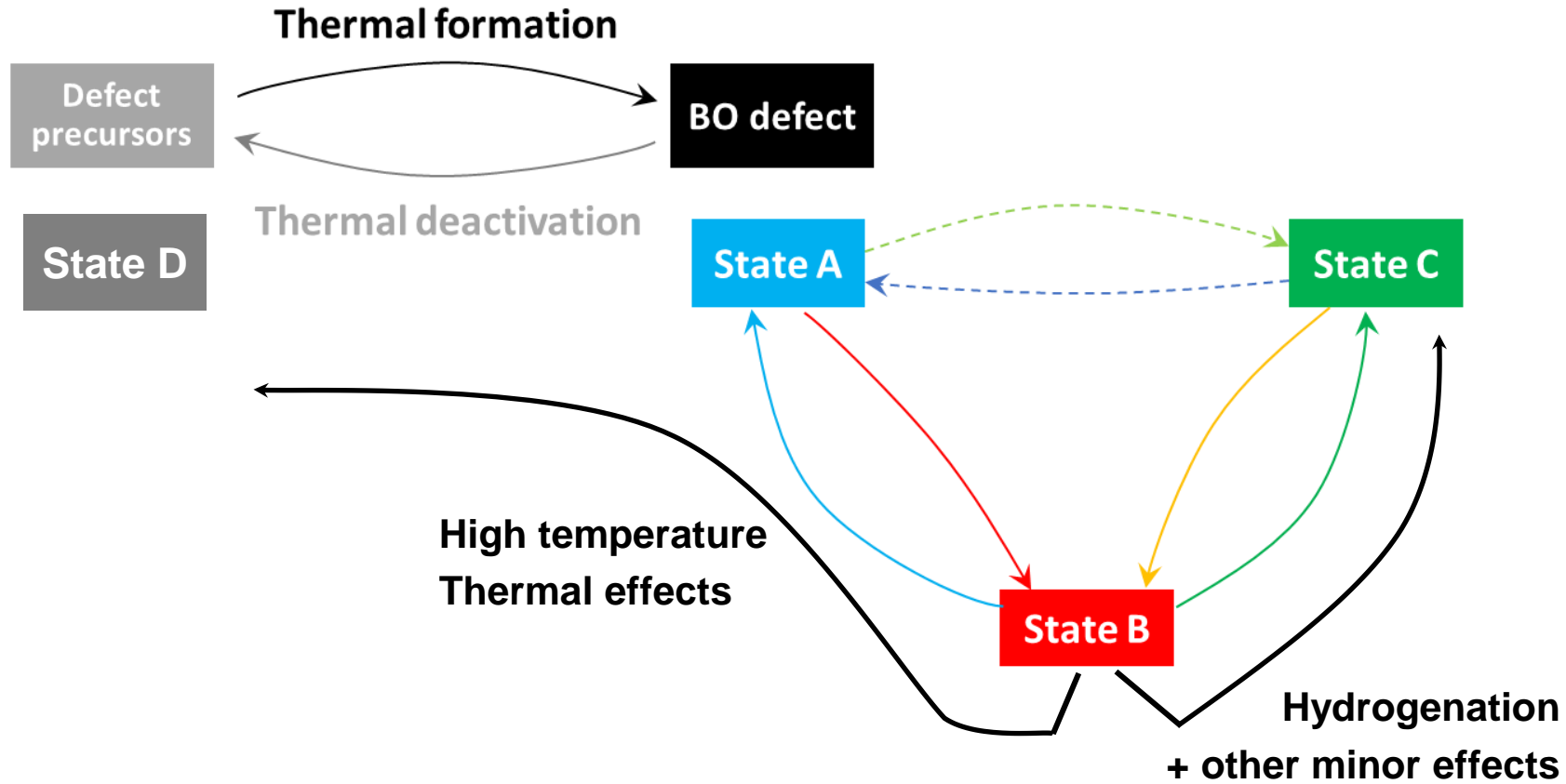
Regeneration only occurs in nitride passivated samples  
(i.e. Regen is hydrogen-related)

# Revision to 3 state model?



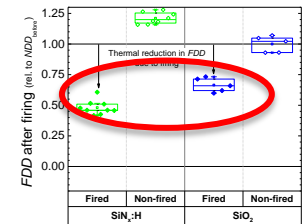
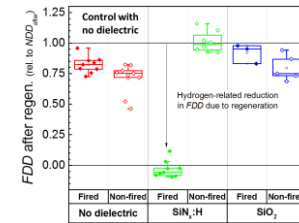
Can they be combined?

# 4 state model

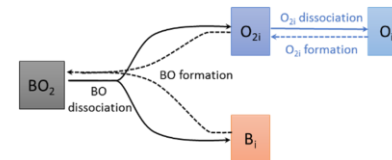


# Summary – Permanent deactivation

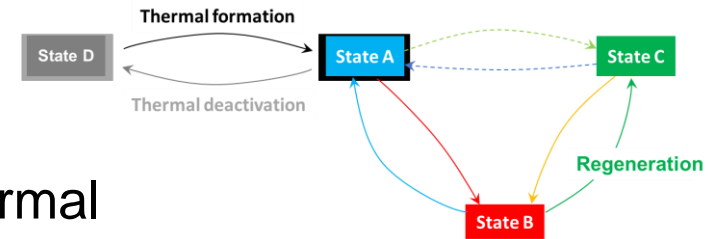
- Effective regeneration requires sufficient quantities of hydrogen. Regeneration could involve other mechanisms (slower).
- Thermal deactivation occurs independent of regeneration. Likely not hydrogen-related.



- Thermal deactivation is likely to be defect dissociation



- 4-state model proposed to account for thermal deactivation





# Implications of this work

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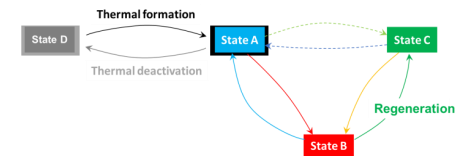
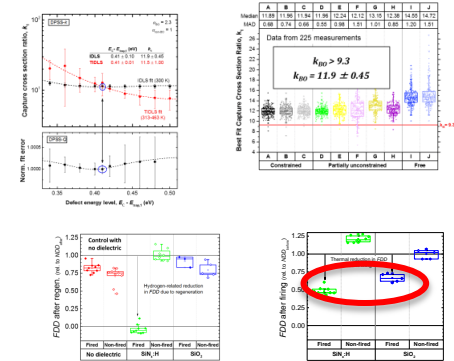
Engineering



# Implications

## 1. Improved understanding of the BO defect

- Recombination properties
- Mechanism of permanent deactivation
- 4-state model



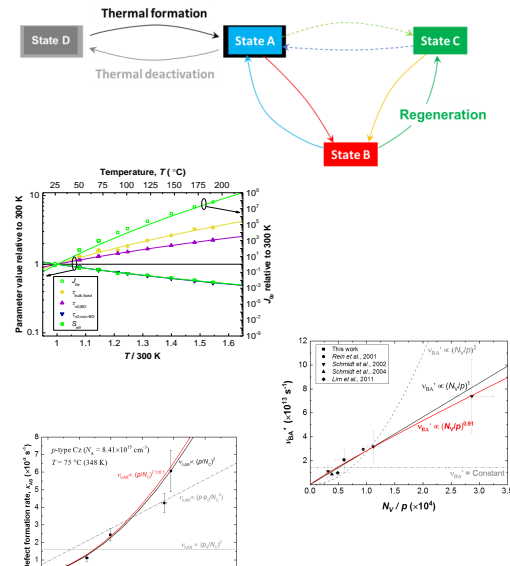
### Impact:

- Easier identification of the BO defect
- Multiple, tailored solutions to mitigate BO defect

# Implications

## 2. Accurate reaction kinetics modelling for BO

- 4-state model
- Conversion from  $\tau_{\text{eff}}(300\text{K})$  to  $\tau_{\text{eff}}(T)$
- Carrier dependence of reactions



### Impact:

- Better estimate of regeneration time-scales for industrial wafers / solar cells

# Acknowledgements

- Funding sources
  - Australian Renewable Energy Agency (ARENA)
  - Australian Center for Advanced Photovoltaics (ACAP)
  - UK Institution of Engineering and Technology (IET) / A.F. Harvey Engineering Prize.
  - Commercial partners (ARENA 1-A060)



# Acknowledgements

- Supervisors: Malcolm Abbott, Stuart Wenham, Matt Edwards
- Hydrogenation group
- Laboratory:
  - MAiA processing team
  - LDOT team
  - Others
- Admin staff:
  - TETB
  - SPREE
- Friends and family

Thank you for your attention

[nnampalli@gmail.com](mailto:nnampalli@gmail.com)



# Motivation

- *p*-type silicon dominant for foreseeable future
- PERC cells seeing an increasing market share
- Surface passivation quality is improving
- “Reliable kWh” is increasingly important

Warranty requirements & degradation for c-Si PV modules

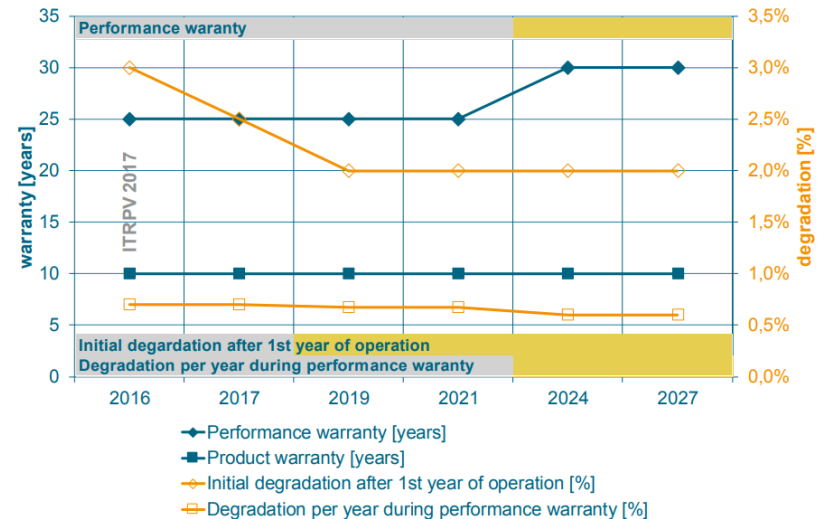


Fig. 48: Expected trend for product warranties and degradation of c-Si PV modules